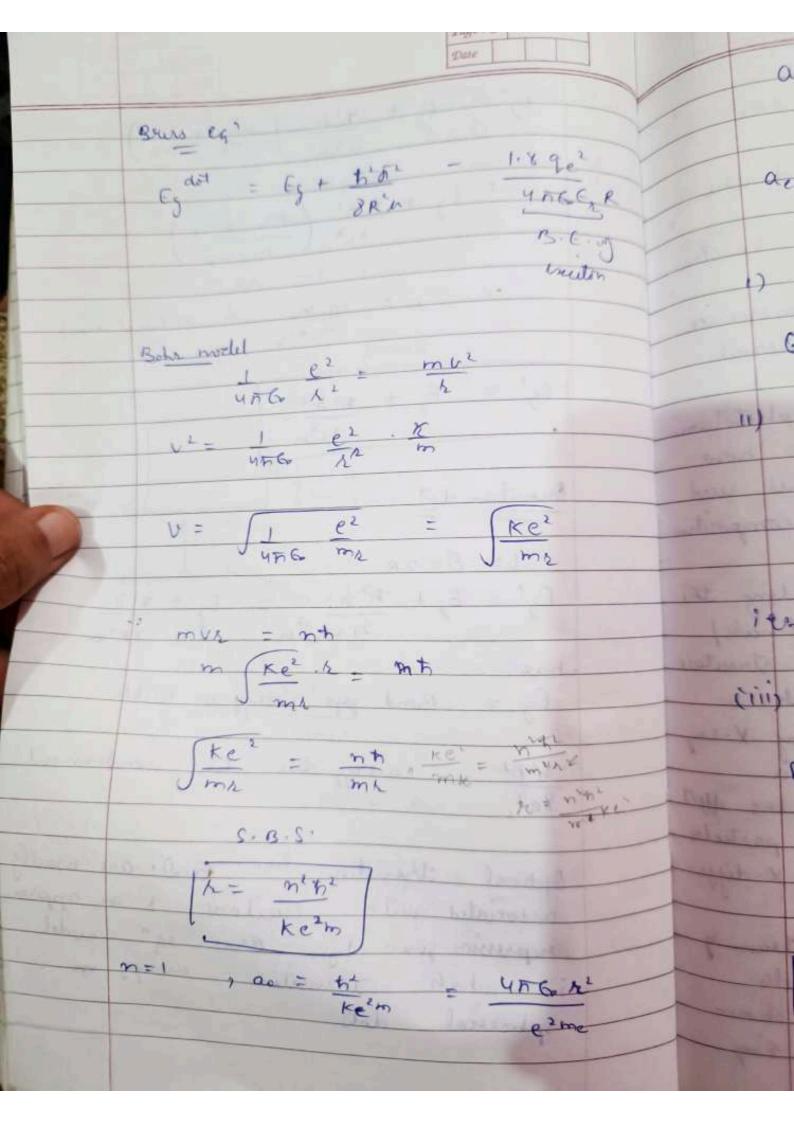
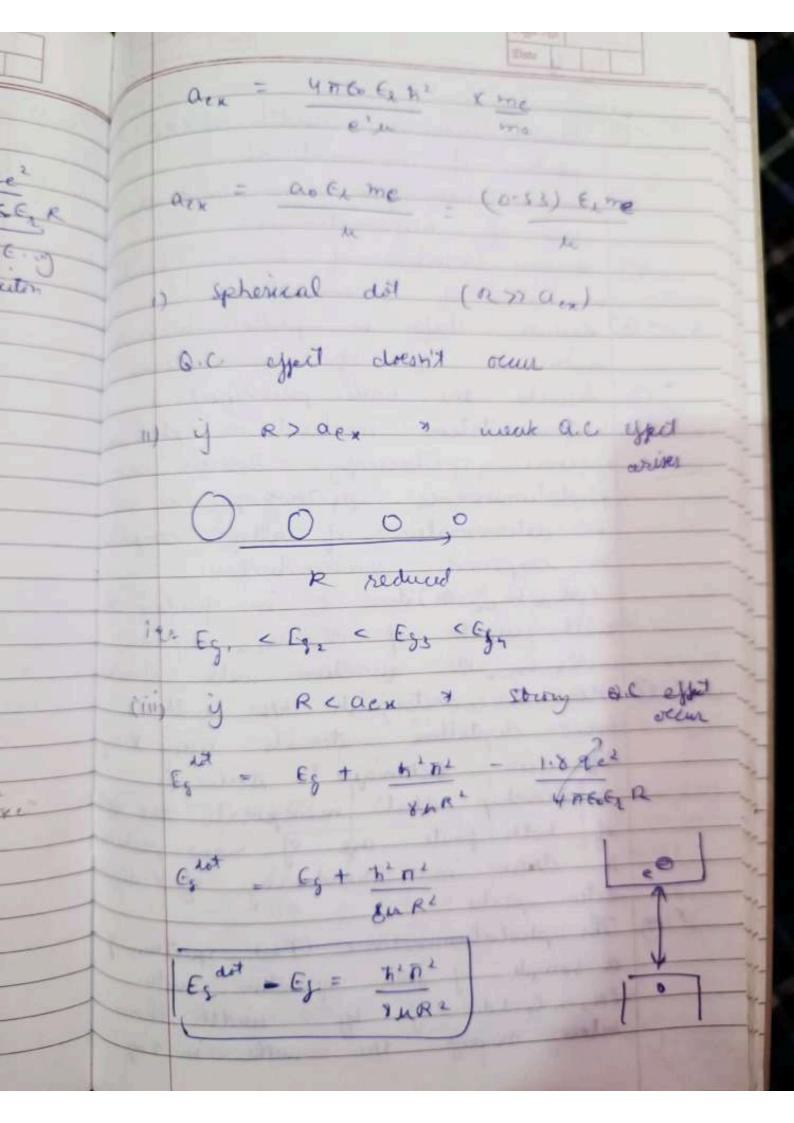
auentum confinement: P-1/2 In nanomaterials, the electronic energy levels are not ats as in bulk but are discrete because of confidencent of elethoric wave from to physical dimensions of particles This phenome is realled Q.C.L in nanoceytals are referred to as quantum dats. The confinement leads to a bransetin from its to discrete energy levels. Levels Es & Nomost-Levels J. Levels J. Level A quantum confined structure is one in which motion of ele Modes are confined in the or more dir by ptl barriers They lie in Q.C regime, Then Their electronic splical proper others of deviale substantielly ferm others of

bulk materials. The discrete structure of energy states leads to a discrete absorption spectrum of nanostructure ig Bulk + namescale icts - directe E'JEn Teg' 7 Em J アーニー かんな Eg = Eg + En + Em Cg' = Eg + m27 2 th + m27 1 th 2 mn1 'y n = m=1 Eg : Eg + h' ñ' + h' h'

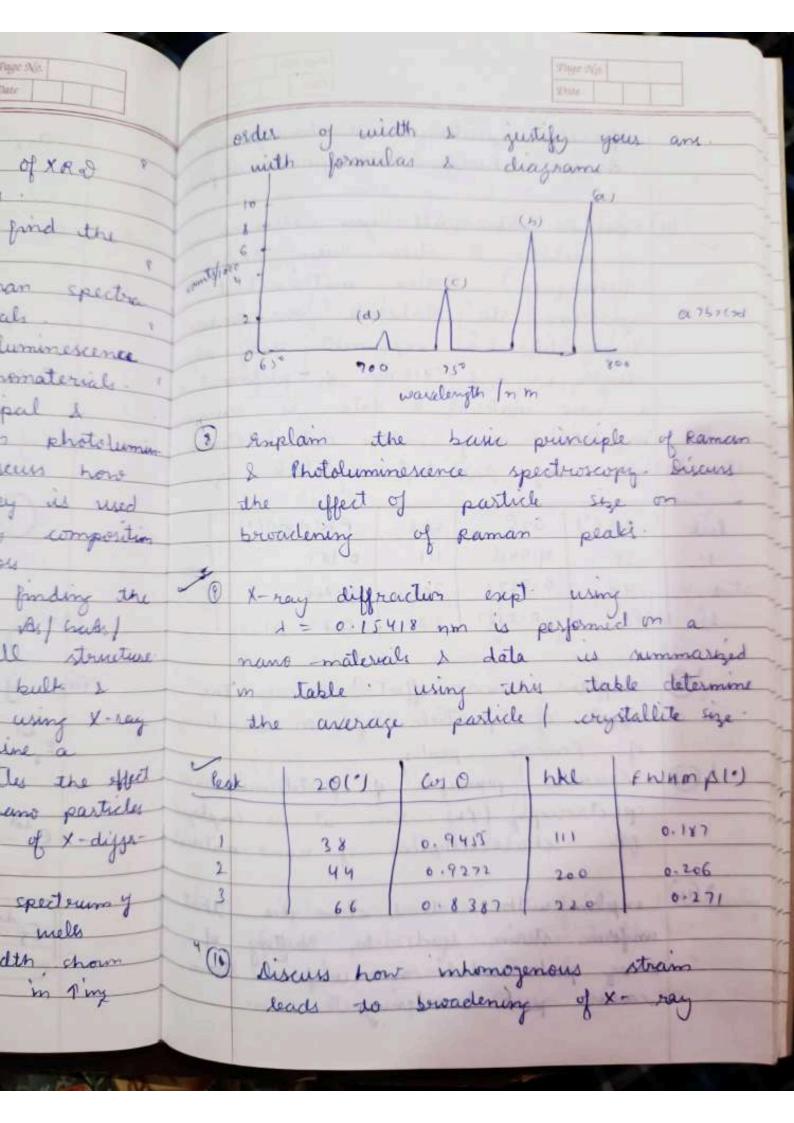
2mel2 2mel2

Eg: Eg + #2 1 [ 1 me + 1 ) drewhuse a = Eg + tini (m++me) m of ·- / = m, m2 reduced mass  $ES' = E_J + \frac{4}{2L^2n}$ mantim dut.  $E_{5}' = E_{5} + \frac{m^{2}n^{2}}{2(2R)^{2}n} = E_{5} + \frac{\pi^{2}n^{2}}{8R^{2}n}$ The Bond pap energy of Bulk The energy due the nontiment Optical transitions in Q.D. are usually expression given by Brus eq well in which transition energy in spherical dols

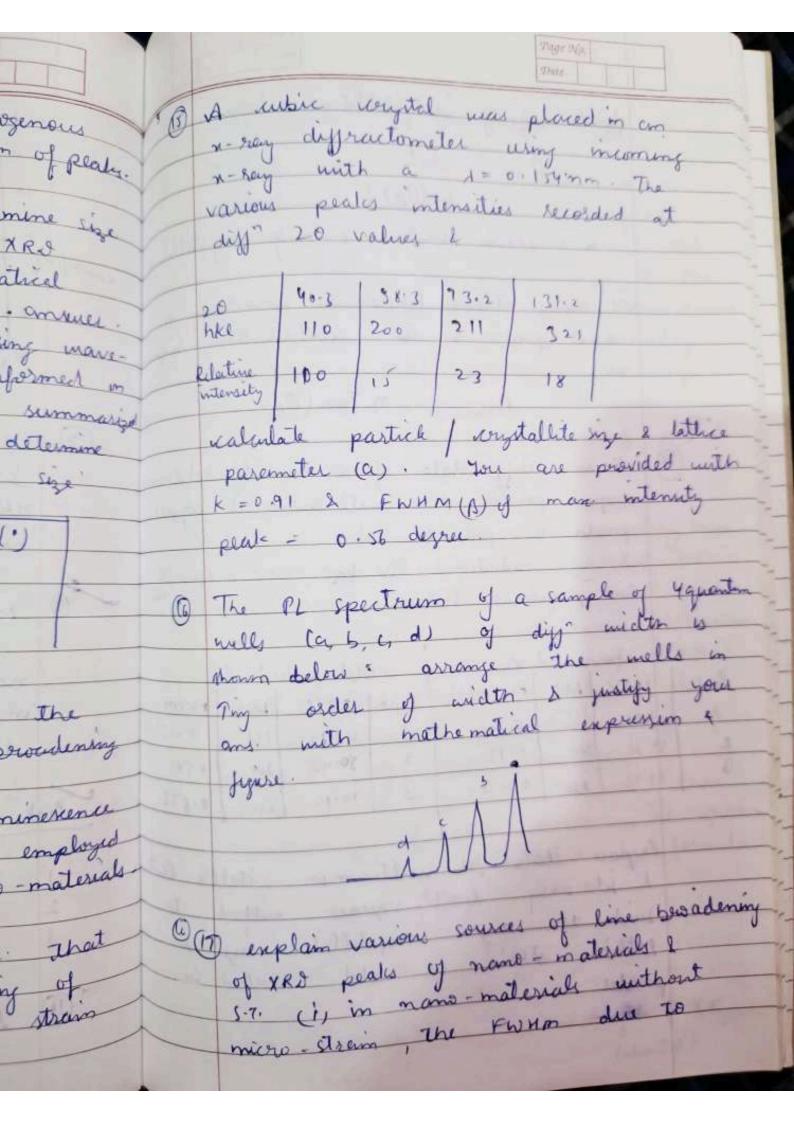




Piggs No. 2mp - ques. order with o O Discuss increase in width of XRD peaks of nanomaterials. @ Discuss how you can find the size of nanomaterials. Diran variation of Ruman spectra in wave of nanomaterials. s & @ Discuss shift in photoluminescence peaks in case of nanomaterials. \* @ Sescribe the basic pruncipal & instrumentation implied in photoluming -escence spectroscopy Discuss how photoluminesence spectroscopy is used in determination of alloy composition in compound remiconductors ( Al x ha, x D) etc & in finding the well windth of Alx har a vas | hads ! Alx box-x as quantum well structure @ now to distinguish 5/w bulk & nano-constalline materials using X-ray diffraction technique? Derine a relationship that incorporate the effect Peak of both finite size of nano particles & strain on broadening of X-diffe--action peals. The photoluminesence (PL) spectrum y a sample of jour quantum mells (a, 5, C, bd) of dip windth show below, arrange the wells in Ting



Stage No. diffraction peaks while homogenous strain whanges the position of peaks (1) Discuss how will you determine ing of particles & strains using XR3 techniques? Derine mathematical expressions to elaborate your comme x-rayediffraction experiment wing mane - length (1) = 0.15418 mm is performed a nano material & data is summary in Table using this data determine the any particle / verystablite size FWHMP() 20 () | Gy 0 hkl 0.9455 0.167 111 38 0.9272 49 200 0.206 66 0.8387 220 0.271 1 explain Roman effect? Discuss The effect of particle size on broadening of Ruman peales; 1 Cescribe principle of photoluminexence exectroscopy (PL). You it is employed for characterization of nano-material "(4) emplim with near & clean die That uniform strain leads to shifting of x-ray peals while non-uniform straws cause peak broadening.



Sinte size of ungstablites is given as 45(Op) L K = schoon comt ; L = any crystallite in XRD plate & its contribution is given Astran = n Ian (OB) (1) X-ray diff. data of a heavily and -world woper ponder & a well annealed wapper pender is presented below X-rey radiation: Cu ka, 1 = 0.100000 Ruk profile : haisian Old moved an Annealed Lu Puede fwam() hko 20(") FWIM leak 2010) Wal 0-465 45.16 111 111 0.260 4331 Sp-30 0:330 50.40 147.0 200 2 200 73.55 174.19 0 -438 0.676 1220 220 Propose data for milliamson - Hall's led I bit wany least square nothed to lattice Arain in cold morted in

Page No. Determination of Particle size ines as Particle size determination is a collective name of techniqual onystallite igu procedure which determine the size, range or mean size of the im is given particle. The particle's size can have importance in no of industry including the chemical mining, posets, agriculture & industries There are various methods of particle ly sold-well size determination! (a) XRD :- X-ray diffraction is very mp experimental technique that has 0.134056 been used in deturnine the years size. The grain size is determined by the broadening of KRS Cu peak. This reak bewadening is 0.415 0.541 0.676 normally caused by finite size of cruzital of the average size of cruzital is below 200 nm then broadening of XRD occur. The ignam size can be icalculated by formula given by betye schere Hall's let thod to iv- 0 = kd me & orlead an K = debye's court , d = mandenyth of XR (0.9) (about 1A)

B = FW Hm of given signal 1- ray reak is desired four the sum of different peak generated from different atoms As name particles have much less atoms Hence, the lattice sum is not able to a broadened The smaller the particle, the broader will be the diffraction Reak. Broadening can be used to measure the size of the particle angle, the diffracted bearn will interfere destructively & results in shorp peak. The destructive inter - ference is a result of summ--ation of all diffracted peales. the clebye schere formula can also be written as D= KI (PS Pc) 1/2 as 0 FWHM of standard sample calculated , In XRD, X- ruys interact with de &

that ele tregin to vibrate as radiations in other die on the sum ich less sum is Plane II the for unstructure raction 2d sin 0 = nd used to particle of Brazzo @ DLS: - It stands for dynamic light scattering. It is also esults in ine inter known as photon co-relation spectre-- ropy & Quari- Static light Summe penics scattering. It is used to determine la con the particle's size in suspension or particles in solution. Ols can measure mans volt size. Smaller particles in suspension undergole random thermal motion known as Brownian motion. The cliameter of particle can be determine by stokes mple einstein relation Juny totale to

Dr = KBT 30n D to Boltzmannia const it = lengt of uncocity D = diffusion welf Ils can measure particles eize upto I'm in diameter. The basic prunciple is simple. The sample is ellering ated by laser beam & fluctuation of scattered light are detected at a particular scattering angle o by a photon detector simple of LS instrument that measure at a fined angle seen determine mean particles size unhereas multi- angle instrument can determine full particle size distribution. OLS is used to sharacterise the size of various particle melecting perstans, polymers, perstans carbotydiate & nanoparticles. John (multiengle)

Page Na. The measurement of particles sego depends upon size it particle cole size of surface structure, particle conc. I types of cons in the medium 3 Raman Effect In 1924, (V Revocen find out shat when beam of light is passed se moto through a transparent substance, Prunciple a small amount of radiation energy is ellemin is reathered. If a parallel beam of fluctuation monochromatic light of frequency dilected ve is incident on a given remple which doesn't absorb the light iple OLS The scattered energy will consists I a fined of some freq radiation called as partiles Rayleigh scattering. In addition mitterment to the mident freq certain discrete freq above or below of meident radiation will be scattered. our particle This is called as Raman scattenten, - very. The Ramers lines appearing at bug lower than the bug. stokes line whereas line observing of freq. higher than the freq. multi angle

canti- stokes lines Variation of Raman Spectra of when an incident photon inter--act with a chemical bond, the chemical bond is excited to higher energy state, most of the it energy would be re-redi incident light which is known as Rayligh scattering: A small portion of energy is transferred a results in excitation modes & The raman process is called as stoke scattering. (Then the sussequent reradiated with a freq. lower than the freq of medent If the particle of atom already present in exciting state then meident photon interact with these I gives on increase in reradiated energy. This is termed as anti-state lines.

Raylish line stolce lines onti state Votov \* Raman lines Raman scattering is also called as enotor scattering Trese are two intertypes of photon scattering:

(1) Elastic scattering:

these is no loss bond, xuted Most of of energy when the particles dimensions ne - sedi are of the order of or smaller than the wavelength of incident that of known ractiation then scattering is called elastric scattering. small ansferred des & (1) Enclastic Scattering: there is a long called as energy. This scattering occurs when a frequired the particle size in larger than the manchenoth of incident radiation This type of scattering is known ready as Raman Scattering Raman scattering is also called as Resonance Raman Then th these radiated spectroscopy. Raman Shift: - It is observed in terms of ware no. I which to reciperate to reciperate to the unit of wavelength I (cm) -1

Trape No. pho Ray In this type of scattering, a sample is illuminated by laser beam (lamp). relationagnetic radiation 1 The from alluminated spot is collected ph with a lens & send thorough a monochromator. Elastic scattered radiation at marelength closer to the RW hardength of incident light are filtered out whereas the other radi--atim of different wavelength are detected by detector-Virtual energy lovel ho Vibrational ensign level General dia showing transition 5/w virtual & misrational energy A from above dia, there are three different pte outcomes:

O The molecule can relan back to the ground state I emit photom of equal energy as that of midest

Page 76s. photon (elastic perviess) & referred as by laser ic suchation 1 The molecule can relax to real rollected phonon state & then emit radiation ough a of energy < that of energy of incident photon as param shift scattering photon attered u to the ase (stoke lines) Thes radiare 3) The third ptl outcome is that in which molecule is already in excited state. This molecule return to the ground state with + 67' energy more than energy of mident photon as antistoke Reman 60+ hv scattering. The pust of antistokes of stole lines scattering €. transition Variation of Raman Spectra of Nanoare thele consider the raman spectra of theram hermanium nan anytal which is produced by gas wondens-I to the -atin showing broadening & shifting of given ware no as the particle eige on of mident

de son singe & more singe & d = 1200 A d = 1600 A 350 300 250 200 Ramon shift (mt) Raman intensity is Remain shift of he Now constal for diff dimens - 800 C - 70 40 60 80 600 120 annualing Time (ms) FWAM of he wystal against annealing Temp. Amrealing time - heat treatment given to sample do get desired information.

Tipe Na Titte Particle Size so 40 60 to 100 tro amounting time of Particle size affect the annealing Inne of he veryttal. application of Ruman spectroscopy It is used to verify now materials of jenes Semaple 10 used to analyze skin depth.

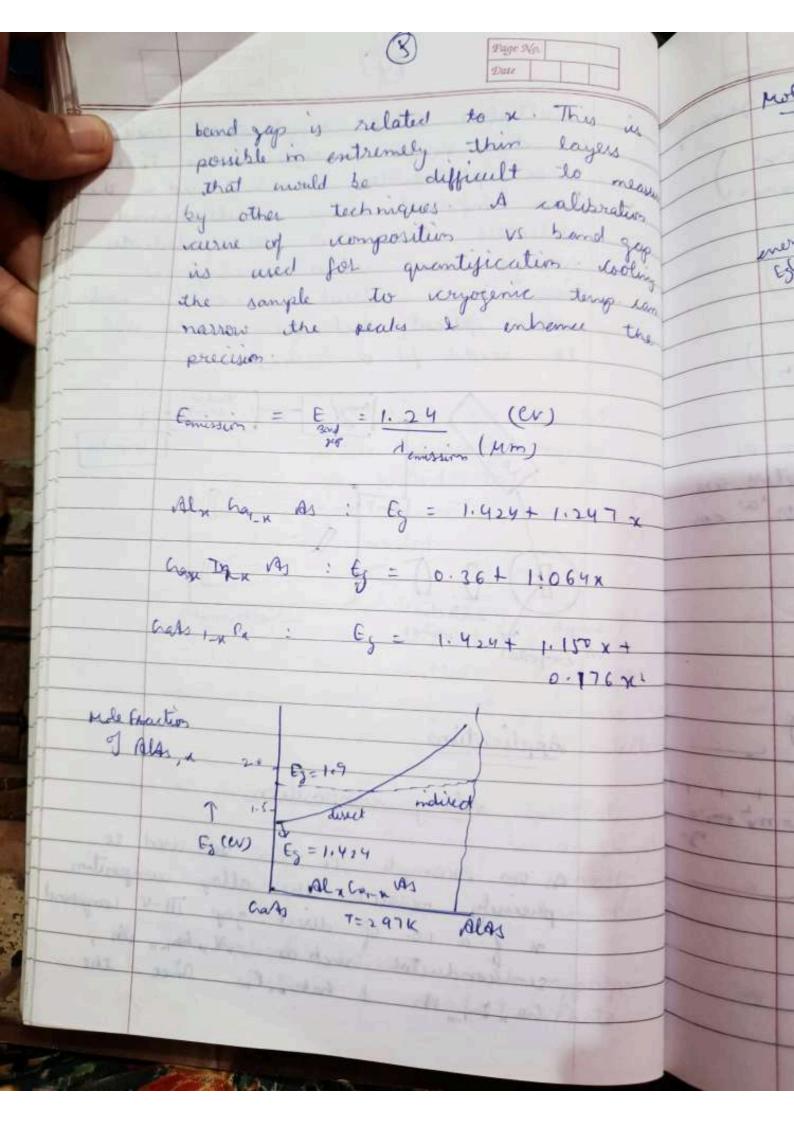
(9) used to identify active pharmacen-- Tical ingredients. B used to measuring the size of molecules less them I was

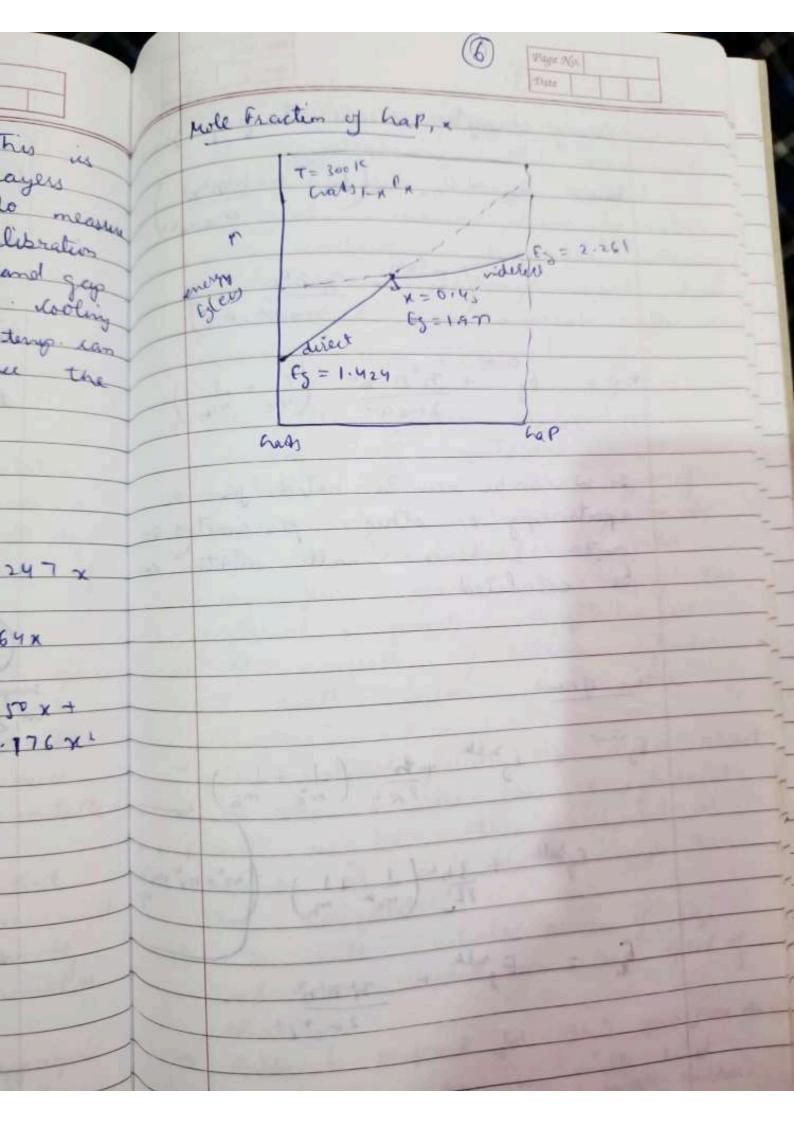
Figer No. (1) ation spectumetry or fluorescence orea teri No Lumingreenee pice emission of light by a material through any process other than blackbody radiation-100 The term photoluminercence (PL) narrow dur This down to any emission of the light that results fewer optical etimulation. the -ati En note cular systems, ne use defi w terminology to distinguish bow ha occident PL processes That tend to be just (sub-microsecond), nuhose emission me eall phiorescence & as other slower ones which are said def to generate phospholescence to p Basic Perinciple egims energy by absorbing of light er from a low to a higher energy be described as 1 state to an existed state of an

aton or molecule, or four V. B. to creation) a S/c wrystal (c.h pair After a system dependent where steristics lifetime in the excited state, which may last from picosecond to many seconds, the eli sigtem will return to the governd state. In luminercent nationals. some or all of the energy released during this final transition is in the form of light, in which care the relaxation is said to be radi--ative The wavelength of this emission is longer than that of the mederal This emitted light is detected dependence of its interestly is analysed to provide information about the prop of the material emperical relation this = Equation +  $\frac{h^{\dagger}n^{\dagger}}{2L^{\dagger}}$   $\left(\frac{1}{m_{e}^{2}} + \frac{1}{m_{i}^{2}}\right)$ emiller Luan se calculated 1= 1.24 (cu)

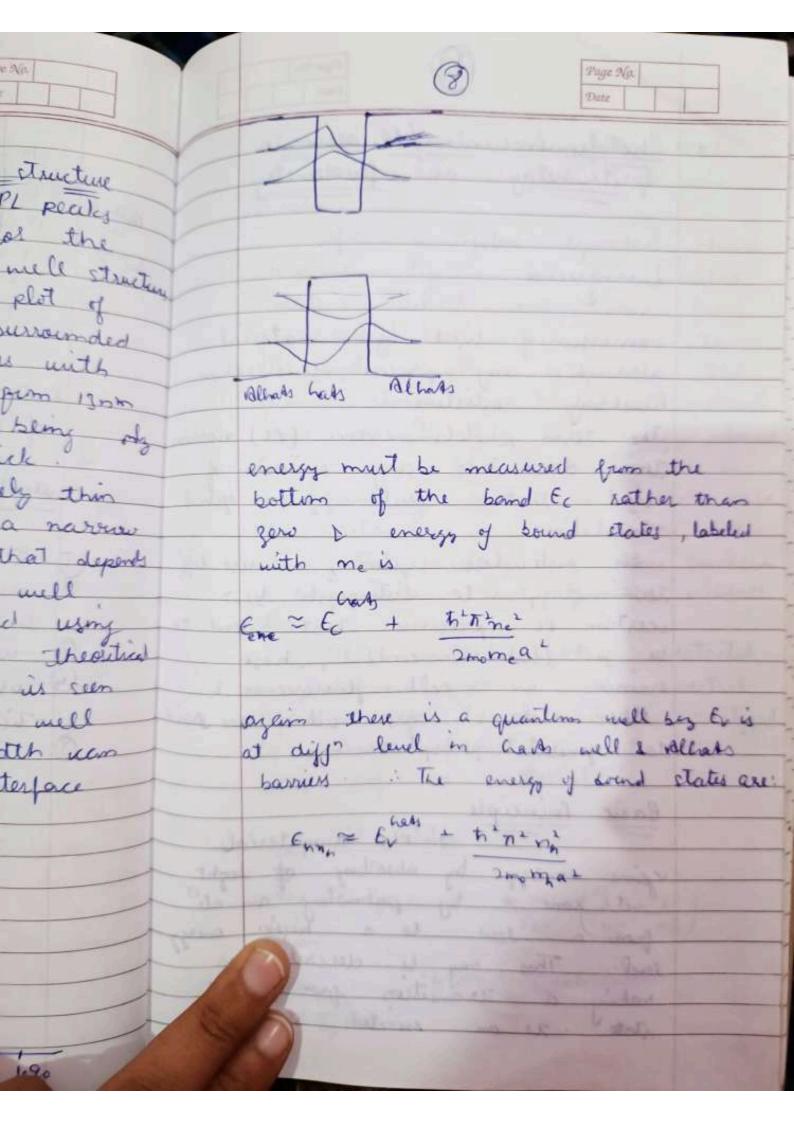
Size of Nano particles Eg. ramo = Eg. talle + the (1 + 1 mg) Insteumentation Jour Basic components make up a PL system a is source of light for excitation. Surface studies generally require a continuous of pulsed laser. A dy of the supplier laser is used of two ability is needed. (s) A sample holder along with ophis for focusing the meident light & m collecting the smitted light. It may allow for conjustat, pressure sell, magnet or electrical contacts (5) A dispersive element for spectral analysis of PL. This may be as simple as a filter but it is usually a rearring grating morochromator ate electronice & readout Photo

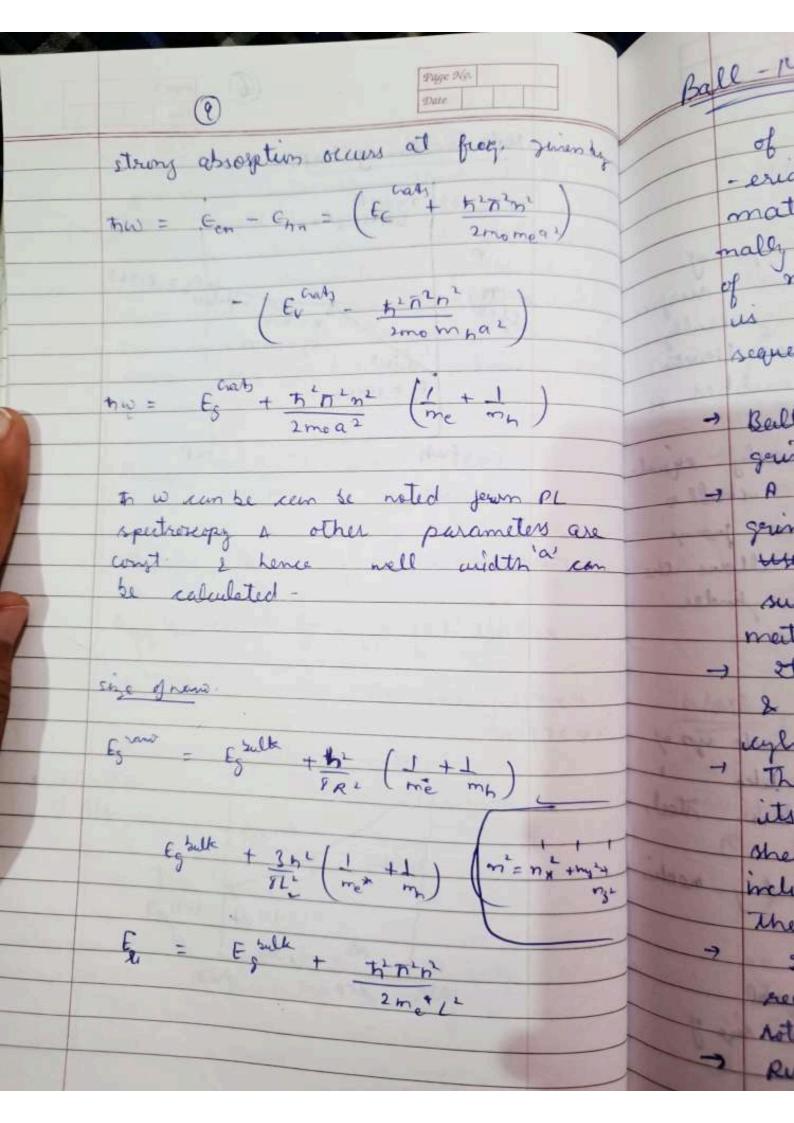
Date -multiplier tubes supply good sensitive for d in visible region & he si or other photodoodes can be used in the near infrared runge Multichannel detectors like cas or pholodiodes times & a streak cornera a nont near optical technique can be used to recold ps of cub ps sample sollection monochromatol petrics Applications sleg composition As an example , Pt can be used to precisely measure the alloy composition x & a no. of direct gap III-v compound semiconductor such as Alyhan its, hantning to I had talk since the





Page No. width of quarter well structure another common use of PL peaks energies to to monitor the windth of quantum well structure Fig show a composite plot of Gats quantum wells surrounded by Alo., has barriers with well windths varying from 1300 to o.snm, the last bling of two atomic layers thick each of these entremely this layers gives rice to a navour Pl peals at an energy that depends on it's thickness. The well width can be measured using peak energy & a shiple theoretical model. The peak energy is seen to be very sensitive to well width it the peak undth icon give an indication of interface sharpness 40 8 9 20 P 1.15 1-70 1.75 1.80 1.85





Ball-Milling 19. Hivenly = 27 is a top down approach of synthesising the name mat-Jo me a s) -erials i use large initial material which war be entermally controlled in the processing of namomaterials (large scale which is reduced to namoscale after a sequence of operation) - Ball milling process is based on gounding of material PL - A Ball mill us the type of les are grinder viz used to grinder to used the rane material into super-fine powder & mining the material, points, pygotechnique It consists of hollow eighnder

& ball present mide the

eighnder

The hollow eighnder viz solates about uts aries & the cons of exhibited shell may be either horizontal or irelined at a small angle to the horizontal an mill whole process of size reduction depend on the spied of - Rubber is poutered for this purpose the the less mean in mills limed much subber.

Construction to consists and parts Hollow cylinder Bally. Hallow white : It is made up of metals. The inner surjace I extinderical shell is generally timed with an abreasion (souther) seasofant material city subber of mangenese steel. the hollow afinderical whell a attached to nott metallic prome I these metallic frames allows the notation of the hollow agrinder at its only = Balls :-The balls are also made up of metal & other material like steel, chronium, stomless steel, ceremic of rubber These balls form the grinding media of the ball mill. the not y sally are equal the ball since depends on size of ( coplenderical)

Inin ciple a ball mill impact the punciple of collision Priction one obj hitting. up of bla material amother a clid ner surface particle particle blu balls? generally Tolles - tous sun (paretin) subber of at propied speed impaction occur early equal at the moving balls hits the shell o material, that wones in som ic frame them while the attrition occurs allows the at low speed by the balls aghinder mores together. Working & the speed of ball mills in of
the process of
size map bay the process of
it made up of like steel, The new material is to be sumpled put into ball mill works companied fill in cylinder upto the -65% of total not of cylinder, the metal ball is till upto 35-40%. ndry media nal j Then the mill is allowed to

- The speed of notation is very imp. over each other ( 8) - 2 ret speed is high, due to high speed centripital force of balls sit on the wall of the englisher : so the ball mill operates correct speed. Stainley naw.

a highly quality ball mills are potenti--ally expensione & can guind minture " run evermous o Tre the surface aread ren rate. There are 2 thypes of ball mill grate thype & overfall thype acc. to indiff ways of material large sized mills are mechanically rolated on their anis.

Solution but small mells normally consists of a cylinderical capped container that sits on two drive shafts. Ilonetary ball mill: is smaller them a common ball with mill & is senerally used in laboratories for research purpose A ball mill can be used for grinding material such as ones. chemicals, ceramic raw material & paints are used in pyrotechniques & the monnyacture of black pointer Pyrotech - Hash pounder (4000at x)

# Khemical Bath Solution The Deposition CBO dechnique involves controlled pricipitation of a compound form - The first CBD thin film were prepared in 1884 & this method was limited to PBS S P b Se fish a long time I level sulphile - After the deposition of Cals a wide sange of khallogende & khalcopyrite material (covalent bonded) have been prepared by this method → 1980, the focus of CBD films slowly turned towards solar energy application. Advantages of CBO of CBO is the simplest cost effective method. - it is possible to deposit multi-compound thin film over a mide range. I rehemical do not require nigh

vacuum & it can be nowed out over at morning lengt inexpensive nethod for lary yell ntrolled industrial application very small. nere bunuple :-- In this technique it is possible Phs to control the film thickness ! Lead sulphide chemical demposition: by varying the deposition parameters such as temp precursor con complex a wide ing agent & the Pri of sol copyrite - The ability of abil method to roat large areas in a reproduction a low cost process. of this method depend on the deposition of thin films from aquelous sell either by parsing a ing werent of by chemical sex 2 20 (BD perocess thin films are deposited on a solid substrate when it is immersed into a delete set of one or more metal salts effective in on agreens sul? p

- The block dia of CAD method 1) motok 21 thermometer 3) mater bath 4) glass bealer n glas slide 7) heater @ Various perocess of thin film deposition in CBO technique substitue substrate suntrate

a ion by ion process a cluster by cluster pewers. - mined process This method the metal echalocogenish films will home we substrate efter by 4 stopss
is eq m 51 is mater & complexing agent in posmation of metal complex species in hydrolysis of the challogende de source. cy pormation of solid film on the substrate-@ The deposition of plans occurs on substrate when the value cinic product exceeds the white product, otherwise it is precipitally I The basic perinciple of CRO is the untrol the chemical next o armonly used complex agent dement com eyent
TEA, NHY CN NH, CE CYHYOG Ag Cd 10

factors influencing the deposition Proces - bath temp - rature & come of the percursors. + nature & come of complexing agent - kn of out - depositive time - nature of substrate (1) Bath temp. I An imp. Jacker that if bath Temp. agent Tres & the K.G. of molecules B films thickness depend on the set 1) Nature & cone of complexing opent - has greater influence on the finalagent sol fest thin john pereparation that mareasite completes that mareasite completes that property atim 3 PM - when bot of nex? bith me the metal complen . They will die the molecule resulting in higher thickness thickness

of the film Q Deposition Jime: The growth of good quality thin films proceeds ecursos. at slow rate cing agent The ass method is untable for producing imijorn trickness in that is # Cluster Beam swappeatin through at is basically a physical vaporation implex deposition technique which is used molecules to deposit this films of growth of nanostructure of materials the adr cluster - gow hundred to for dozens of atom together brund by some force are called agent the priod cluster Muster can be made using atoms of moleatomic chirles complexin pereparation atums 000 00 000 egrete: 0 00 Ise the 0-0

Fage 9(0ichister can be in peure porm or in mixed form. - Size of constituting is to nm - no. of particles (constituting 2 to severed thousand - CBD is a method of significant of nam structure material - it is a special type of PVD (Physical vapour deposition technique) this can be finally used to materials. righ degree of parity & enact nanoparticle size control mano particly elusters 200 collectedon a cuto a cold plate 20000 [ = material 1 to be evaporated moking eluster

- Asgregates nanging from a few atom to a fow thousand of atom are known as chisters are produced & carried in supersonic acuster tells about the solid behaviour expensions way @ A supersonic expension is achieved when high povers. (1-6 alm) gas 1400-1200) mission into a vacuum. ique) - electrine structure & the lattice structure of material play on rup of the cluster of nanostructure & name composite earticles films.

- it is Type of Lotton - up approaches
2 used in significant of Law materials. tedo cuto Jupersonic expension have several advantages for cluster manipulation once effusive beam. That makes this approach very structure from deposition of mano structure from dechnique

Date a cluster may also be defined as an ensemble if bound along of metermediate is intermediate in size ble molecule & a balle. of a certain kind of molecule - atomic cluster can be either peux species of mixed formed from mixed atomic species an gas phase synthesis manaparticles
on made by individual atoms a
molecule up to the desired size condensation of a supersaturated superior of by them cal sen atom jewn jullerence discipled it when the

empoisin chamber l as an Juleview deposition chamber ate in olely rolecule dustr source Vacuumpengs er telle high press - ) low press. ( supersonic expension) dDP = 2V (P,-Pd) Fr

dt = (2 Mm kgT) /2 Fr mopartick Op = particle dienviles V1 = vol. P, = partial prom of zer Fi = Fuchs - subject to in the continuum regime the seite of alp. 40v. (P.Pa)F2

out Dp +3 7 1) = dipuism will. of ges or vapour

-> CBE is a bottom up approach which involved alons by atoms, molemble by molecule or chester by eluster manipulation for synthesy o) namostructures - Aggregates ranging juvo a jour along molecular of ions do few thousand of atoms or milecules of way which may be held together by various types of sinding jorce with DE 3100 a yew tenth of ev to several er are known as cluster & are produced & carried in supersoric expansion in which a high press ges is expended through small orifice into vaccum. working of 20 empansion chamber, the cluster beam Jewn the chifter source indergoes supersonic exponsion through the small orifice provided in the inpension chamber - The seeded part of cluster seam enter to and (deposition) thember through the skimmer which's used for the geometrical writing - ment of eluster beam.

ch substrate placed in deposition chamber Chron Her by & hence by elester bear deposition formed the substrate, nanopartiely are thery + vactum reury are provided to vereate atmed vaccum in exponsion & deposition chambers so as to weate for rusand press. I to avoid any undestrable which impurity. 4 0.6 The process of deposition of ranoparticle several en substrate involves a procuses: are @ Particle Formation ic a Growth rensmall 1) Particle formation: The Marting material is vapowized from a hot source into eleviter a gas of low density using joule ource heating thermal planner of laser ablation. Rapid cooling grapour prinide leads to supersaturation jollowed by homongenery mucleation with the formation of ist product cluster mber wromth - The roundy foremed particle h'b mjine seviface growth (addition of alonger

molecules de particles) or by rogulation (in elastic particle - allising) ing generally sollowed by walsune linerging of a or more particles on contact to form single particle) The particle sharps may be applied the rate if particle growth by egulation 7 y the particle dia is much smaller Than the mean free path of ges, as it boundly the case with duster. The wagulation theory of que mobile regime has do be applied. magnet The above 2 protesses usually take place simultaneously. today auderate! advantages: O gives high degree of pursity

advantages: O gives high degree of pursity

advantages: O gives high degree of control: pleases tigh rateral resolutions & Will focusing. focusing.

# Jon Beam Deposition (Bottom - up) - This is kottom up approach for the synthesis of nanomaterials. lisin) lenge 00 -> The A Thin film deposition method that peroduces the high quality film Heil with excellent perecision & tight control oner film thickness. material to a target through the application of on ion beam Heallimoted steet magnet in herm I pump analyse O plasma westin im source 1 im entracted from plasma the state and the state of - An in beam deposition apparatus typically uonists I am im source, im optics 1 the deposition starget.

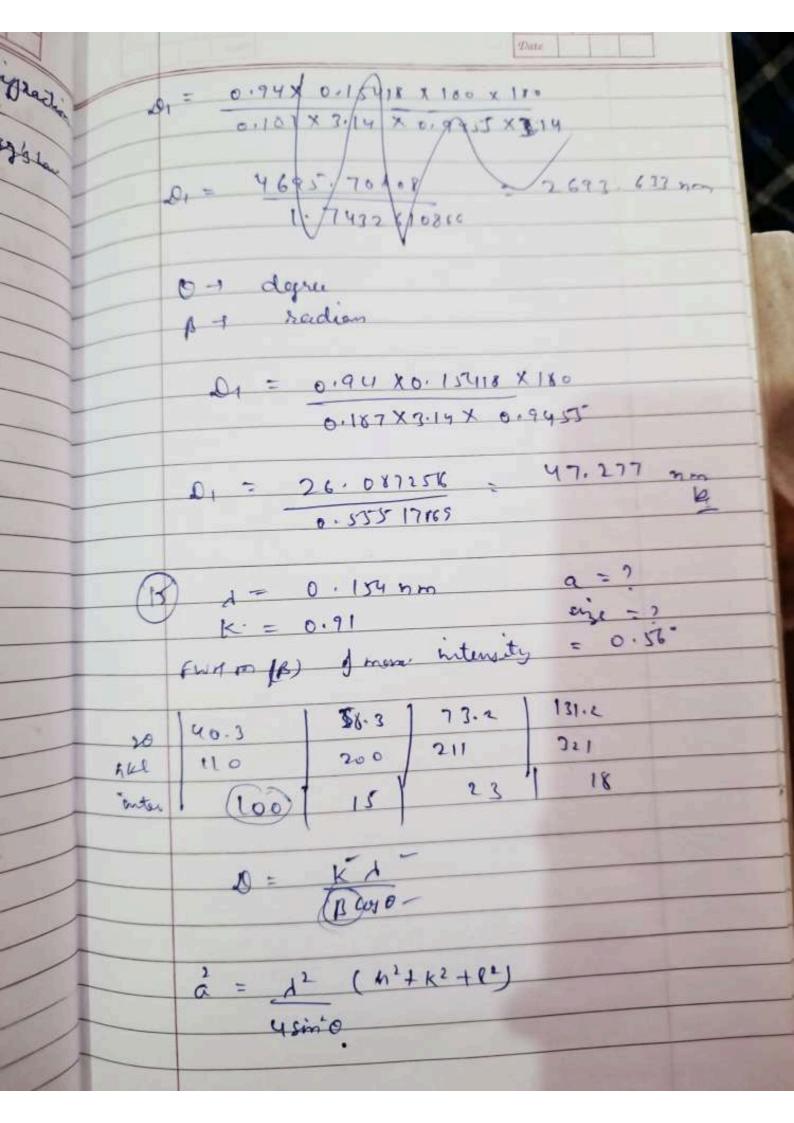
optimalty va mans analyzer can be meorparated. In the ion source, source material in the form of gas an evaporated sold of a sold (lig.) are irriged - For atonic bon Ise, ele conigation field ionization of ecathodic are source are used - reathorie are sources are used particul -arly for carbon ion deposition. - The in are other accelerated Joseph or deflected army high vol. or mag field. -ation described atomic species are circized & accelerated in an electric field - The energy range of you ar losson under high vaccum. is introduced as a gas into the auth the atom of gas wriging there of may fuld & electric juld are Tis the efficiency of ion process of confine the plasma. Only in y in be single type energy are deflected by precisely 90 on their jollow slightly naterial diff theireactories that reparate Sated them from become Lonized wisales - Thus purified been is gocused & accelerated to high energy & penetrate The surface dayers of substance buyer partin resulting the change in its umposition & micro structure. of which effect the material persperty docume - The penetration depth runge from 0.01 - juna depend on the target materials & types of ion & their - The arg renetration depth is called The range of ion. -) due to implomation a new surfaces is formed nutrich is part of the substrate with modified non position 0500 4 in which alon. to in 1 It a low temp perocess & thermal distortion of component dues not exist. @ et is used in s10 device jabrication By this technique it is possible to obtain nanoparticles or compounds & alloys of more than one element.

Page No. O high energy beam weate some defects in the substrate material. elisadu: Field ionization: et is the ionization of interse dectric field, usually counted by a sharp electrocle at a high potential. Nathodic are source: In cathodic are sown a high current supply to electric are to stribe & raporize the source material within a vacuum more transment. # Sof - gel and the same of the same

X-ray tid is em radiation. X day are produced by bombarding high energy ele on heavy metal Acce to Mosley's low every element mas its unique signature in sorm y & amission dis as slits. 101 roughal digraction bezog its shorter 1. diffraction is the main technique used to identify constal structure.

The when a 11'rd beam diffracted from a um ringle slit causes a path difference of dan o & when incedent become is also at an angle O then the path diff. is 20 sin O ALETTED XV PERSON poin din o

when atomic planes all as digration slits. The the contractine interference is defined by Briagy's law 1 2 dsm 0 = nd) incident. diproceted lang 0 = K1 BCOSO (9) 1= 0.15411 pm , K = 0.94 D, = 0.94X 0.15418 0.187 x 0.9415 Connect in radion Tradions = 110' 1 hadi = 180° degree - radian -



MPGI

16 (ð)

JO

oT levels. confine Where spacin confine smous A

function

Fig. 2.2. Physical model for metal Potential energy box (3D)

electron from the metal is given by function i.e., work required to pull an

2.1.1. Free Electron Gas in One Dimension

metal and one at rest in vaccum and EF is the fermi energy of the metal. where W represents the energy difference between an electron at rest inside the  $M = \Lambda^0 - \mathcal{R}^E$ 

0=1  $\infty = \Lambda$ 

using quantum (Fermi-Dirac) statistics. distribution of these electrons in various energy levels are determined The possible electronic energy states in potential energy box and

box is assumed to be zero and at the boundaries, it is infinitely large confined to move between 0 < x < L. The potential function within the the x-axis in one dimensional (I-D) box (see fig. 2.3). The particle is Let us consider a particle of mass m moving in straight line along

Schroedinger wave equation as function  $\psi$  of the electron corresponding to energy E is determined from The electron is confined to remain always within the potential box and wave

$$0 = \psi \frac{\mathcal{L}m\mathcal{L}}{\mathcal{L}_{A}} + \frac{\psi^2 b}{\mathcal{L}_{xb}}$$

where A and B are constants to be determined from the boundary conditions and  $\psi(x) = A \sin kx + B \cos kx$ where E is kinetic energy of the electron. The general solution of this equation is

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OX

ve m

3)

D)

2)

 $k = \sqrt{2mE/\hbar}$ 

...(5)

Boundary conditions are (due to continuity of w),

$$\psi = 0 \text{ at } x = 0$$
= 0 at  $x = L$ 
...(6)

Putting  $\psi(x)=0$  when x=0 in eq. (4), we get

$$\psi(0) = A\sin k.0 + B\cos k.0$$

 $0 = 0 + B \times 1$ B=0

Using  $\psi(x=L)=0$ , eq. (4) yields

$$\psi(L) = A \sin k. L = 0$$

 $A \neq 0$  (otherwise  $\psi(x) = 0$  for all values of x), hence

$$sink.L=0$$

OF

or

OT

$$k = \frac{n\pi}{L} \tag{8}$$

where n = 1, 2, 3.... Thus the eq. (4) for the allowed wave function becomes

$$\psi_n(x) = A \sin\left(\frac{n\pi}{L}\right). x \qquad ...(9)$$

The allowed energy values or eigen values can be obtained from equations

(5) and (8) as

$$k = \frac{n\pi}{L} = \sqrt{\frac{2mE}{\hbar^2}}$$

$$E_n = E = \frac{n^2\pi^2\hbar^2}{2mL^2} \qquad ...(10a)$$

 $E_n = \frac{n^2 h^2}{8m L^2}$ ...(10b)

$$E_n \propto n^2$$
 ...(11)

A graph between  $E_n$  and n is shown in fig. 2.4. It shows that the energy levels of particle (here, electron) confined within the box are quantized or discrete. The spacing between energy levels depend upon n and L, where n is known as quantum number. Thus confinement of electron leads to quantization of its energy

To evaluate the value of A, we normalize the wave function  $\psi_n(x)$  for which

$$\int_{0}^{L} \psi_{n}^{*}(x) \psi_{n}(x) dx = 1$$

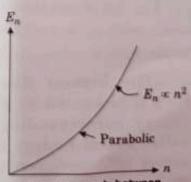
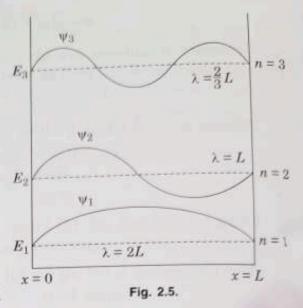


Fig. 2.4. Graph between

or 
$$A^{2} \int_{0}^{L} \sin\left(\frac{n\pi}{L}x\right) \sin\left(\frac{n\pi}{L}x\right) dx = 1$$
or 
$$\frac{A^{2}}{2} \int_{0}^{L} \left[1 - \cos\left(\frac{2n\pi}{L}x\right)\right] dx = 1$$
or 
$$\frac{A^{2}}{2} \int_{0}^{L} dx = 1$$
or 
$$\frac{A^{2}}{2} \cdot L = 1 \quad \text{or} \quad A = \sqrt{\frac{2}{L}}$$
Substituting it in eq. (9), we get 
$$\psi_{n}(x) = \sqrt{\frac{2}{L}} \sin\left(\frac{n\pi}{L}\right)x \qquad \dots (12)$$

First three energy levels and **eigen** functions corresponding to n = 1, 2, 3 are shown in fig. 2.5.



### 2.1.2. Fermi Energy

We know that free electrons in a crystal or metal are distributed among various discrete energy levels in accordance with Pauli's exclusion principle, according to which no two electrons can be in the same quantum state. In other words, if one electron is in a specific quantum state, the other electron must then be in a different quantum state.

In a metal, an electron in an energy state is specified by n (principal quantum number) and  $m_s$  (magnetic spin quantum number). One quantum state denotes one set of values of n and  $m_s$ . There are two possible values of  $m_s$  ( $\pm 1/2$ ) for each value of n. Hence each energy level corresponding to principal quantum number n can have two quantum states ( $m_s = \pm 1/2$ ) and hence can accommodate a maximum of two electrons – one of spin up  $\left(i.e., m_s = +\frac{1}{2}\right)$  and other of spin down  $\left(m_s = -\frac{1}{2}\right)$ .

Fig. 2.6 shows the filling up of 7 electrons in different energy levels. The energy levels with  $n \le 4$  would be occupied while the levels with n > 4 would be empty.

"The highest filled energy level at T=0 K is known as Fermi level and the energy corresponding to Fermi level is called Fermi Energy  $E_F$ ". In this case, the energy level corresponding to n=4 is known as Fermi level.

If N is the total number of electrons to be accommodated, then if n is even, we can write

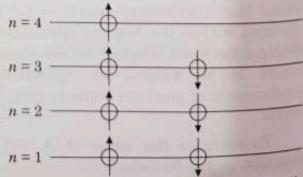


Fig. 2.6. Filling of electrons in various energy levels

$$2n_F = N$$
all quantum number of the Fermi level. Hence for  $n = n_F$ , eq.

where  $n_F$  is the principal quantum number of the Fermi level. Hence for  $n = n_F$ , eq. (10) becomes

$$\begin{split} E_F &= \frac{\hbar^2}{2m} \left( \frac{n_F \cdot \pi}{L} \right)^2 = \frac{\hbar^2}{2m} \left( \frac{N \cdot \pi}{2L} \right)^2 \\ &= \frac{\hbar^2}{2m} \left( \frac{\pi N}{2L} \right)^2 = \frac{\hbar^2}{2m} \left( \frac{N}{4L} \right)^2 \end{split} \tag{14}$$

where (N/L) is the number of electrons per unit length. For 3-D metallic crystal (i.e., a cubical box), the eqn. (12), (10) and (14) transform respectively as

$$\psi(r) = \sqrt{\frac{8}{L^3}} \sin\left(\frac{\pi n_x x}{L}\right) \sin\left(\frac{\pi n_y y}{L}\right) \sin\left(\frac{\pi n_z z}{L}\right) \qquad \dots (15)$$

$$E_n^2 = \frac{\hbar^2 k^2}{2m} = \frac{\hbar^2 \pi^2}{2m L^2} (n_x^2 + n_y^2 + n_z^2) \qquad ...(16)$$

$$n^2 = n_x^2 + n_y^2 + n_z^2.$$

where

$$n^{2} = n_{x}^{2} + n_{y}^{2} + n_{z}^{2}.$$

$$E_{F} = \frac{\hbar^{2}}{2m} \left( \frac{3\pi^{2} N}{V} \right)^{2/3} \qquad (17)$$

where  $n_x$ ,  $n_y$  and  $n_z$  are positive integers,  $\sqrt{\frac{8}{r^3}}$  or  $\sqrt{\frac{8}{V}}$  is the normalizing constant and V is the volume of the 3-D box or crystal.

### 2.1.3. Density of (Electronic) States

density of states "The total number of available electronic states per unit energy interval is known as density of states". The density of states is denoted by g(E)and is given by

$$g(E) = \frac{dn}{dE} \tag{18}$$

where dn is the number of electronic states present in the energy range E to E+dE.

According to free electron theory of metals, each energy level contains two electronic states, one with spin up and the other with spin down, therefore

th spin up and the 
$$g(E) = 2 \times \frac{dn}{dE}$$
 ...(19)

From eq. (10a), we have

$$E = \frac{\hbar^2}{2m} \left(\frac{n\pi}{L}\right)^2$$

...(20)

or 
$$\frac{dE}{dn} = \frac{\hbar^2}{2m} \left(\frac{\pi}{L}\right)^2 \times 2n = \frac{n h^2}{4 m L^2} \qquad \therefore \quad \hbar = \frac{h}{2\pi}$$
 or 
$$\frac{dn}{dE} = \frac{4 m L^2}{n h^2}$$
 Substituting this value in eq. (10)

Substituting this value in eq. (19), we get

$$g(E) = \frac{2 \times 4 mL^2}{nh^2} = \frac{8mL^2}{h^2} \times \frac{1}{n}$$

Again from eq. (10a), we have

$$E = \frac{\hbar^2}{2m} \left(\frac{n\pi}{L}\right)^2 = \frac{n^2 h^2}{8 m L^2}$$
$$\frac{1}{n} = \left(\frac{h^2}{8mL^2 E}\right)^{1/2}$$

Hence.

or

$$g(E) = \frac{8mL^2}{h^2} \times \left(\frac{h^2}{8mL^2 E}\right)^{1/2}$$
$$= \frac{4L}{h} \left(\frac{m}{2E}\right)^{1/2}$$

$$g(E) \propto \frac{1}{\sqrt{E}}$$

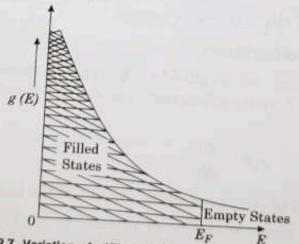


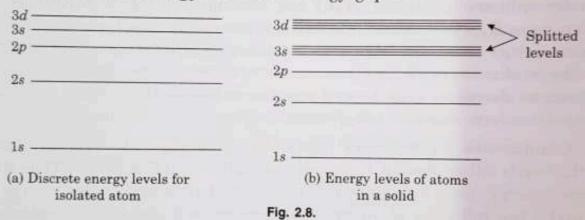
Fig. 2.7. Variation of g(E) with E for a 1-D metallic crystal

Fig. 2.7 shows the variation of density of states g(E), with energy E and it indicates that all energy levels upto  $E_F$  are filled with electrons.

## 2.2. THE BAND THEORY OF SOLIDS

We know that electrons in an isolated atom possess discrete energy levels 1s,2s, 2p,.... etc. (fig. 2.8 a). These levels are filled with electrons in the order of

increasing energy. When these isolated atoms combine to form a solid, they arrange themselves in an orderly pattern, called a crystal. In a crystal, due to periodicity, each atom is in the electrostatic field of neighbouring atoms. The discrete energy levels of individual atoms are no longer valid. Instead, due to interaction between atoms, each discrete level splits into closely spaced sub-levels (fig. 2.8b). The number of sub-levels is equal to the number of atoms N in the solid. Since N is very large  $(N \simeq 10^{23} \, \text{cc})$ , therefore separation between these sub-levels is very small ( $\approx 10^{-23} \, \text{eV}$ ). Hence these sub-levels are almost continuous in energy and thus are said to form energy bands. The first energy levels of various atoms constitute the first energy band, the second energy levels form the second energy band and so on. The energy band formed by valence electrons of atoms is called the valence band. This band is the highest occupied band. The next higher band is known as conduction band and is normally empty. Now these allowed energy bands are in general separated by regions which have no allowed energy states. Such regions are termed as forbidden energy bands or energy gaps.



The splitting of energy levels does not take place for lower levels 1s and 2s because the electrons in these levels (being deep inside the atoms) are not

significantly affected by the presence of other atoms. Further the 2p level does not begin to split until the interatomic separation becomes smaller than actually found in case of sodium. In fact 3s level is the first occupied level to be splitted into sub-levels. In higher energy levels splitting occurs because electronic wave functions overlap significantly to give rise to interaction between them. Fig. 2.9 shows the splitting of various energy levels in terms of interatomic separation.

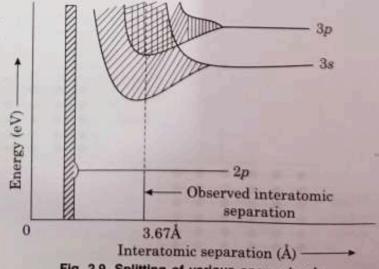


Fig. 2.9. Splitting of various energy levels

# 2.3. DISTINCTION BETWEEN CONDUCTORS, INSULATORS AND SEMICONDUCTORS ON THE BASIS OF BAND THEORY OF SOLIDS

The energy band structure is a characteristic feature of a solid. Thus different solids possess different band structures which gives rise to the wide range of electrical properties observed in them. Depending on the nature of band occupation by electrons and the width of forbidden energy bands, all solids can be classified into conductors, semiconductors and insulators.

I. Insulators: Insulators are those substances in which the valence band is completely filled with electrons and the conduction band is empty and there is a large forbidden energy gap ( $\approx$  5eV or more) between these two (fig. 2.10a). Because of this large gap, electrons can not be thermally excited easily across this gap from the valence band to the conduction band. Therefore an external electric field (i.e. electric potential) can not cause any significant current. For this reason, the electrical conductivity of such materials is extremely small and may be regarded as zero under ordinary conditions. NaCl and Diamond are good insulators having forbidden gaps  $E_g \approx 6 \, \mathrm{eV}$ . When the temperature of an insulator is raised above room temperature some of the valence electrons may acquire enough energy to cross over to the conduction band giving rise to an extremely small current. So resistance of an insulator decreases slightly with increase in temperature. Thus the resistance of an insulator have negative temperature coefficient of resistance.

II. Conductors: Conductors (particularly metals) are those substances in which the bands either overlap or are only partially filled (fig. 2.10c). Thus electrons and empty energy states are intermixed within the bands so that electrons can move freely under the influence of an external electric field. As a result metals have

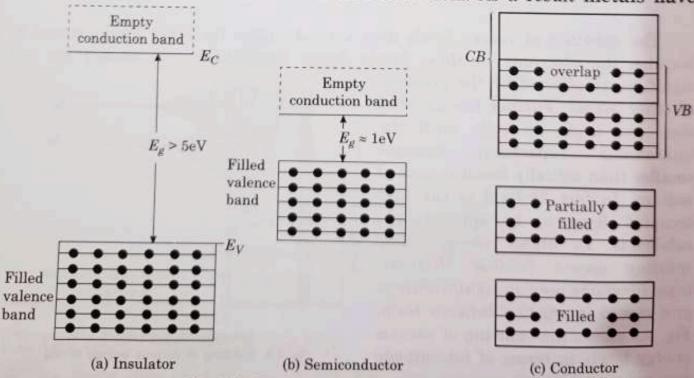


Fig. 2.10. Energy band structures at absolute zero

high electrical conductivity. However, their conductivity decreases with increase in temperature. The electrical resistance (or resistivity) of metals increases with increase in temperature due to increased number of collisions at higher temperatures. Hence metals have a positive temperature coefficient of resistance. Due to overlapping, the valence band also acts as the conduction band.

Consider the case of sodium (Z=11). The electronic configuration of Na is  $1s^2 2s^2 2p^6 3s^1$ . Thus the valence band (formed by 3s levels) is only partially filled. On application of electric field, electrons can freely move into empty states within the same partially filled band. This makes sodium a good conductor. Another metal magnesium  $(Z=12, 1s^2 2s^2 2p^6 3s^2)$  is also a good conductor because in it, there is overlapping of 3s and 3p bands. Current flow is possible in an electric field.

Thus the observed electrical properties of conductors (metals) can be explained on the basis of their band structure. In fig. 2.10c, the conduction band is abbreviated as CB, whereas valence band as VB.

III. Semiconductors: The band structure of semiconductors is similar to that of insulators at absolute zero temperature i.e. a filled valence band separated from an empty conduction band by a forbidden gap which has no allowed energy states. However, the band gap energy  $E_g$  is much smaller in semiconductors than in insulators. For example, the semiconductor Si has a band gap of about 1.1 eV compared with 6 eV for diamond. The other popular semiconductor Ge has still smaller band gap of 0.72 eV. Due to relatively small band gaps of semiconductors, electrons may be thermally or optically excited from the valence band to the conduction band. Thus a significant number of electrons may be thermally excited across the gap into the conduction band at room temperature. As a result their resistivity decreases with increase in temperature. Hence a semiconductor has a negative temperature coefficient of resistance.

At absolute zero temperature, the filled valence band has no empty states into which electrons can move. Also in the empty conduction band, there are no electrons which can move into vacant energy states. Thus there will be no conduction at all on applying external electric field. Thus a semiconductor behaves like an insulator at absolute zero temperature. The band structure of semiconductors is shown in fig. 2.10b. Their conductivity can also be increased by the controlled addition of suitable impurities in a process called doping.

### 2.4. ENERGY BANDS AND BAND GAPS OF SEMICONDUCTORS

The important properties of semiconductors such as electrical, optical, magnetic etc. depend strongly on the manner in which energy of the loosely bound electrons depend upon the wavevector k in reciprocal (or k) space. The electron momentum p is given by  $p = mv = \hbar k$ . Let us consider three-dimensional crystals, particularly III–V and the II–VI semiconducting compounds, which have a cubic structure (a=b=c). The electron motion expressed in the coordinates  $k_x$ ,  $k_y$ ,  $k_z$  of reciprocal



### Fig. 2.15b. Band structure of Ge

### 2.5. EFFECTIVE MASS

dw/dK 1.e.,

the computations.

altered masses, electrons and holes can be treated as almost free carriers in most of is done to account for the influence of the lattice on charge carriers. By using their the charge carriers in a solid, we have to use altered values of particle masses. This periodic potential of the lattice. Thus while applying equations of electrodynamics to In a crystal, electrons are not completely free, instead they interact with the

electric field s is present. It's particle velocity v will be equal to the group velocity Let us consider an electron with wave vector K in the region where external

$$\frac{Mp}{\omega p} = \alpha$$

If w be the angular frequency of the electron waves (i.e., de broglie waves

associated with electron), then its energy 
$$E=\hbar\omega$$

From equations (1) and (2), 
$$\frac{1}{4K} \frac{dE}{dt} = 0$$

We consider the hypothetical case in which there is only one electron in the brillouin zone under consideration. Then in a time interval dt, electron energy increases by

$$dE$$
 = work done by the electric force ...(4)  
=  $(-e\varepsilon) dx = -e\varepsilon v dt$  From equations (3) and

where dx is the displacement of the electron during time dt. From equations (3) and

(4) 
$$dE = -\frac{e\varepsilon}{\hbar} \left( \frac{dE}{dK} \right) dt$$

Therefore 
$$\hbar \frac{dK}{dt} = \frac{d(\hbar K)}{dt} = \frac{dp}{dt} = -e\varepsilon \qquad ...(5)$$

where  $p = \hbar K$  is the crystal momentum. Equation (5) is analogous to Newton's law of motion for the electron in a periodic lattice.

On differentiating eqn (3), we get

$$\frac{dv}{dt} = \frac{1}{\hbar} \frac{d}{dt} \left( \frac{dE}{dK} \right) = \frac{1}{\hbar} \frac{d^2 E}{dK^2} \frac{dK}{dt}$$

$$= -\frac{e\varepsilon}{\hbar^2} \left( \frac{d^2 E}{dK^2} \right) \text{ on using eqn (5)}$$

$$-e\varepsilon = \left[ \frac{\hbar^2}{(d^2 E/dK^2)} \right] \frac{dv}{dt} \qquad \dots (6)$$

or

This equation is of the type

Force = mass × acceleration

Thus the quantity within square bracket in eqn. (6) may be regarded as the mass. It is known as the effective mass of the electron and is denoted by  $m^*$ . Hence

$$m^* = \frac{\hbar^2}{d^2 E / dK^2}$$
 ...(7)

represents the effective mass of an electron in a band with a given (E, K) relationship. Here  $d^2E/dK^2$  represents the curvature of the band. Hence the curvature of the band determines the electron effective mass. The shape of the energy bands in three dimensional K-space determines the value of effective mass. The electron effective mass will be smaller in strongly curved bands (e.g., Γ) and larger in those bands which have small curvature (e.g., L or X).

The band structure of GaAs is shown in fig. 2.16. The binary compound GaAs is a direct band gap material with a band gap of 1.43 eV at room temperature. It has

direct (at K = 0) conduction band minimum  $\Gamma$  alongwith two higher-lying indirect minima L and X in its conduction band

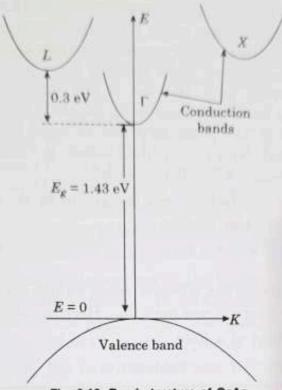


Fig. 2.16. Band structure of GaAs

For a band centered at K = 0 (e.g.,  $\Gamma$  in above figure), the (E, K) dispersion

relation near the minimum is usually parabolic given by 
$$E = \frac{\hbar^2 K^2}{2m^*} + E_g \qquad ...(8)$$

In this case, the effective mass  $m^*$  turns out to be a constant. Similarly, for a free electron,

$$E = \frac{\hbar^2 K^2}{2m}$$

$$\frac{d^2 E}{dK^2} = \frac{\hbar^2}{m}$$

$$m^* = \frac{\hbar^2}{(d^2 E / dK^2)} = m$$

Thus for a free electron, the effective mass is equal to its actual mass. However for an electron moving in a periodic potential, the effective mass is different from actual mass of the electron i.e.,

$$m^* \neq m$$

In this case  $m^*$  varies with energy E or wavevector K. The electron behaves like a particle with variable effective mass. Thus effect of periodic potentials means replacement of m by  $m^*$ .

In many conduction bands the (E,K) relationship is not parabolic, rather they have complex dispersion relations which depend on the direction of electron transport with respect to the principal crystal directions. In such cases, the effective mass is a tensor quantity. Further in fig. 2.16., the curvature  $d^2E/dK^2$  is positive at the conduction band minima, but is negative at the valence band maxima. Thus the electrons near the conduction band minima have positive values of effective mass whereas the electrons near the top of the valence band have negative effective mass. Valence band electrons with negative charge and negative mass move in an electric field in the same direction as holes with positive charge and positive mass. For materials with nearly filled bands,  $m^*$  will be negative. For holes near the top of valence band,  $m^*$  will be negative.

The effective mass of an electron in a metal can be determined from cyclotron resonance experiment. For most metals,

$$\frac{m}{2} \le m^* \le 2m$$

The following table shows the effective mass values for semiconductors Ge, Si and GaAs in terms of the electron rest mass  $m_0$ . Here  $m_n^*$  denotes the effective mass of electron whereas  $m_p^*$  that of a hole.

Table 2.1.

### 2.6. FERMI SURFACES

In a solid, at very low temperatures the energy bands are filled with electrons upto a certain level, called the **Fermi level**. The energy corresponding to this level is called the **fermi energy**  $E_F$ . All levels with  $E > E_F$  are empty. In three dimensional K-space the set of values of  $K_x$ ,  $K_y$  and  $K_z$  which satisfy the equation  $\hbar^2 (K_x^2 + K_y^2 + K_z^2)/2m = E_F$ , form a surface called the **fermi surface**. All  $(K_x, K_y, K_z)$  energy states that lie below this surface are full, and those above this surface are empty. The fermi surface encloses within it all the electrons in the conduction band that carry electric current. Thus we can say that **fermi surface of any metal is the surface of constant energy**  $E_F$  in the momentum (or K-) space. At absolute zero of temperature, it separates the unfilled quantum states from the filled ones. The shape of the fermi surface plays an active role for determining electrical properties of metals.

The fermi surface of a good conductor such as copper (electron density  $n=8.5\times10^{22}$ ) or silver (electron density  $n=5.86\times10^{22}$ ) can fill the entire brillouin

ly to be r. Thus -3/2 lation of slower

> cm<sup>2</sup>/V-sec when silicon is doped with 10<sup>17</sup> donor atoms per cm<sup>3</sup>. doping) concentration at room temperature. For example, intrinsic suicon at T=300 K has electron mobility  $\mu_n = 1350$  cm<sup>2</sup> N-sec which decreases to just 700

such as a semiconductor. Some excitons are intrinsically unstable with respect to an exciton. It is electrically neutral. It is an analog of positronium atom in a solid electrostatic (i.e., coulombic) interaction. The bound electron-hole pair is called decays into a free electron and free hole. All excitons are unstable against the ultimate recombination process in which the electron drops into the hole An electron and a hole may be bound together through their mutual attractive

attractive coulomb force. Its energy levels are given by The positronium atom is the bound state of an electron and a positron under the

$$\mathcal{E} = -\frac{q^2}{8\pi \epsilon_0 a_0 n^2} = -\frac{6.8}{n^2} \text{ eV}$$
 ....

 $a_0 = \text{Bohr radius} = \frac{4\pi \in_0 h^2}{h^2}$  $m_0q^2 = 0.0529$ nm

 $m_0$  = free electron (and positron) mass =  $9.1 \times 10^{-31}$  kg

q =charge on an electron

 $n = \text{principal quantum number} = 1, 2, 3, \dots, \infty$ .

half of the ground state energy of the hydrogen atom. This is because the effective For ground state (n=1), the energy of positronium atom is just -6.8 eV which is mass of positronium is half of that of the bound electron-proton pair in hydrogen atom.

In a semiconductor the electron is in the conduction band, and the hole is in the valence band. The effective mass of electron  $(m_e)$  and hole  $(m_h)$  are less than the mass  $(m_0)$  of a free electron. The effective mass of an exciton (bound electron-hole pair)

$$m^* = \frac{m_e \cdot m_h}{m_e + m_h} = \frac{m_e}{1 + (m_e / m_h)}$$
 ...(2)

If  $m_e << m_h$ , then effective mass of exciton  $m^*$  becomes comparable with the electron effective mass. For example, if  $m_e / m_h = 0.2$ , then  $m^* = 0.83 \ m_e$ . This is the case with GaAs. Also for these materials  $7.2 < \epsilon / \epsilon_0 < 17.7$  where  $\epsilon_0$  is dielectric constant of free space and  $\epsilon / \epsilon_0$  is relative dielectric constant. Thus these two factors decrease the exciton energy E' relative to the energy of positronium atom. Exciton energy levels are therefore given by

$$E' = \frac{(m^*/m_0)}{(\epsilon/\epsilon_0)^2} \frac{q^2}{4\pi \epsilon_0 a_0 n^2} = \frac{13.6(m^*/m_0)}{(\epsilon/\epsilon_0)^2 n^2} \text{eV} \qquad ...(3)$$

These two factors (i.e., effective mass and relative dielectric constant) also increase the effective Bohr radius of the electron orbit, which is expressed as

$$a_{exci} = \frac{\epsilon/\epsilon_0}{m^*/m_0} a_0 = \frac{0.0529}{m^*/m_0} \text{ nm}$$
 ...(4)

For GaAs,  $m*/m_0=0.059$  and using the relative dielectric constant for GaAs, we get

$$E'_0$$
 = 4.6 MeV  
 $a_{exci}$  = 11.8 nm

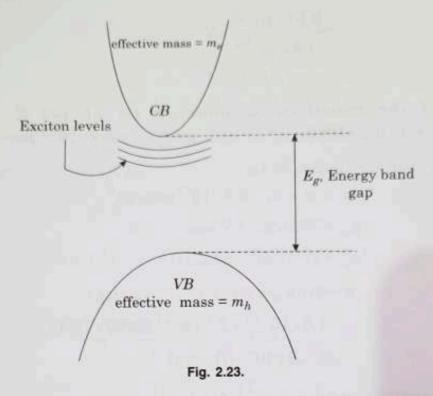
and

where  $E_0'$  is the ground state energy of exciton in GaAs. The effective Bohr radius of exciton (= 11.8nm) suggests that an exciton extends over quite a few atoms of the lattice. Its radius in GaAs is comparable with the dimensions of a typical nanostructure. An exciton exhibits characteristic optical spectra.

### 2.11. TYPES OF EXCITON

Two limiting categories of excitons are as follows:

I. Mott-Wannier Exciton: This is the weakly bound exciton as the one discussed above. The average electron-hole separation is large in comparison with a lattice constant. Its energy levels are similar to positronium atom as shown in fig. 2.23, though respective levels have lower energy values compared to positronium. Exciton levels lie in the forbidden gap. Excitons may be produced when photons of energy lower than the band gap energy,  $E_g$ , are absorbed by the crystal. Almost all the excitons encountered in semiconductors and in nanostructures are of the Mott-Wannier type.



II. Frenkel Exciton: A strongly or tightly bound exciton, called a Frenkel exciton, is similar to a long-lived excited state of an atom or a molecule. It is small in size and is localized on any atom in the crystal. An ideal Frenkel exciton will travel as a wave throughout the crystal, but the electron is always close to the hole. The excitation wave of an exciton travels through the crystal just as the reversed spin of a magnon travels through the crystal.

## Solved Examples

Ex. 1. Calculate the fermi energy when it is given that :  $\frac{N}{L} = 0.8 \text{ electrons per Å, } h = 6.6 \times 10^{-34} \text{ Js, } m_e = 9.1 \times 10^{-31} \text{ kg.}$ 

Sol. The fermi energy in one dimensional case is given by

$$E_F = \frac{h^2}{2m} \left(\frac{N}{4L}\right)^2$$

Substituting various values, we get

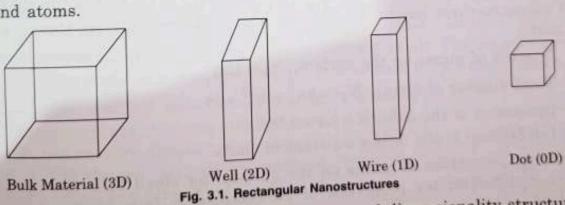
$$\begin{split} E_F = & \frac{(6.6 \times 10^{-34})^2}{2 \times 9.1 \times 10^{-31}} \left( \frac{1}{4} \times \frac{0.8}{10^{-10}} \right)^2 & \therefore \quad 1 \text{Å} = 10^{-10} \text{ m} \\ = & 0.0957 \times 10^{-17} \text{ J} \\ = & 9.57 \times 10^{-19} \text{ J} \end{split}$$

## 3.2. CLASSIFICATION OF LOW DIMENSIONAL MATERIALS

Bulk Material: It is a three dimensional structure in which there is no confinement along any direction. All of its dimensions are larger than the exciton Bohr radius. The particle is free to move throughout the volume of the material. No quantization of the particle motion occurs i.e., particle have a continuous range of energies between a minimum and maximum.

Low dimensional structures are classified on the basis of number of reduced dimensions they possess. Dimensionality refers to the number of degrees of freedom possessed by the particle. The low dimensional structures, on the basis of dimensionality , are of the following types :

- 1. Quantum Well: It is a two-dimensional nanostructure in which there is confinement along one direction and particle is free to move in other two directions (i.e., in a plane). Particle possess discrete (or quantized) energies associated with the confinement dimension. Particle energies are continuous along the other two (unconfined) dimensions.
- 2. Quantum Wire: It is a one dimensional nanostructure in which there is confinement along two directions and particle is free to move in the third direction. Particle has discrete energies associated with these two directions of confinement and continuous along the third (unconfined) direction.
- 3. Quantum Dot: The extreme case in which confinement of the particle occurs in all the three directions, results in a zero-dimensional nanostructure, called quantum dot. In this case, the number of degrees of freedom of the particle is zero. Particle has discrete energies associated with its motion along all the three directions. Examples of zero dimensional objects are-nanoparticles, clusters, colloids, nanocrystals, and fullerenes. Quantum dots are composed of several to a few thousand atoms.



From above discussion it is obvious that reduced dimensionality structures are labeled according to the remaining degrees of freedom in the particle motion, rather than by the number of confinement directions.

### 3.3. QUANTUM SIZE EFFECTS

The properties of a material are characterized by a specific 'length scale' usually on the nanometer dimension. If the physical size of the material is reduced

tant The the the side of a

> nanostructure is reduced below the electron de Broglie wavelength doping level is required to have any significant electron concentration if size of the quantum dots are characterized with very small concentration of electrons. A higher semiconductor. Quantum structures such as quantum wells, quantum wires or

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# 3.4. QUANTUM CONFINEMENT

of energy states leads to a discrete absorption spectrum for a nanostructure. properties deviate substantially from those of bulk materials. The discrete structure they lie in the quantum confinement regime, then their electronic and optical from continuous to discrete energy levels. When materials are so small that comparable to the exciton Bohr radius. The confinement leads to a transition particle, quantum confinement occurs when the nanocrystal radius becomes therefore nanocrystals are also referred to as quantum dots. For a semicronductor continuous as in the bulk but are discrete (shown by the existence of finite density of dimensions of the particles. This phenomena is called quantum confinement and states), because of the confinement of the electronic wave function to the physical In small nanocrystals (i.e., nanomaterials), the electronic energy levels are not

A quantum confined structure is one in which the motion of the electrons and holes are confined in one or more directions by potential barriers. If the charge carriers are confined along one direction and delocalized (i.e. free) in the other two directions, then the resultant structure is a quantum well. When the confinement occurs in two dimensions and the carriers are delocalized in the remaining third dimension, then the resultant structure is a quantum wire or nanowire. A quantum dot may have shape of a tiny cube, a short

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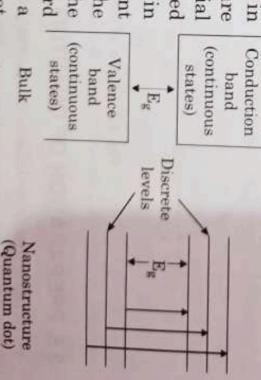


Fig. 3.2. Transition from continuous to discrete energy levels

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cylinder, or a sphere with nanometer dimensions and exhibits confinement in all the three dimensions. There is no delocalization in this case. The following table summarizes the confinement and delocalization dimensions for various nanostructures.

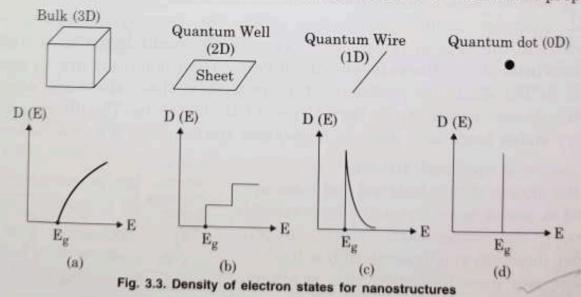
Table. 3.1.

Quantum Structure	Confinement Dimensions	Delocalization (or free Dimensions
Bulk conductor	0	3 (x, y, z, say)
Quantum Well/Superlattices	1 (z)	2 (x, y)
Quantum Wire	2 (x, y)	1 (z)
Quantum Dot/Nanocrystals	3(x, y, z)	0

As more number of the dimensions is confined, more discrete energy levels can be found, i.e., carrier movement is strongly confined in a given dimension.

Nanostructure		Representation
Quantum Well	$\longleftrightarrow$	Particle in 1D box
Quantum Wire	$\longleftrightarrow$	Particle in 2D box
Quantum Dot	$\longleftrightarrow$	Particle in 3D box

The density of states D(E) determines the various electronic and other properties and as shown in Fig. 3.3, D(E), differ dramatically for each of the three nanostructure types. Thus the nature of the dimensionality and of the confinement associated with a particular nanostructure have a noticeable effect on its properties.



## 3.5. PREPARATION OF QUANTUM NANOSTRUCTURES

There are two different approaches of making quantum nanostructures :

I. Bottom-Up Methods: In the bottom-up approach, material and device are built from molecular components which assemble themselves chemically by

principles of molecular recognition. This is carried out by a sequence of chemical reactions which are controlled by catalysts. This bottom-up approach is widespread in biology where enzymes (working as catalysts) assemble amino acids to construct living tissues that forms and supports the organs of the body. It is based upon self assembly of atoms or molecules into a structure.

Bottom-up methods should be capable of producing devices in parallel (simultaneous production) and are therefore, cheaper than the top-down methods. There are many examples of self-assembly based on molecular recognition in biology, such as (i) Watson-Crick base pairing, and (ii) enzyme-substrate interactions.

II. Top-down Methods: This approach of preparing nanostructures starts with a large scale object or pattern and gradually reduces its dimension or dimensions without atomic level control. Top-down methods use a technique called lithography. In this technique, we shine radiation through a template onto a surface coated with a radiation-sensitive resist. The resist is then removed and the surface is chemically treated to produce nanostructure. A resist is a soft material. Polymethyl methacrylate  $[C_5O_2H_8]_n$ , a polymer, is a typical resist material. Fig. 3.4. shows the lithographic process of obtaining a quantum wire or quantum dot starting from a GaAs quantum well formed on a substrate.

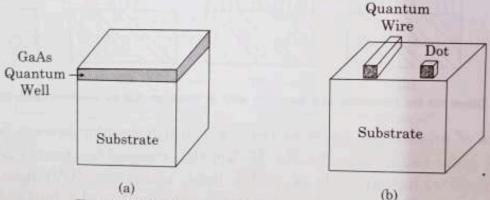


Fig. 3.4. Formation of Quantum wire or dot from a well

The whole lithographic process takes place in a number of steps as shown in Fig. 3.5. In the first step, a radiation sensitive resist is placed on the surface of the sample substrate (Fig. 3.5a). An electron beam (used as a radiation) is made to fall in the region where the nanostructure is to be placed (Fig. 3.5b). This can be achieved either by using mask that contains the nanostructure pattern or by a scanning electron beam that falls on the surface only in the desired region. The radiation chemically modifies the exposed region of the resist and makes it soluble in a developer. If the exposed material is etched away by the developer and the unexposed region is resilient, the material is called a positive resist. And if unexposed region is etched away by the developer, then resist is called a negative resist. In the next step (Fig. 3.5c), developer (e.g., tetramethylammonium hydroxide) is applied to remove the irradiated portions of the resist.

Fig. 3.5. Steps for the formation of a quantum wire or quantum dot by electron-beam lithography

Laser beams as radiation source are suitable for quantum-dot fabrication, electromagnetic radiation such as visible light, ultraviolet (UV) light, or X-rays. use neutral atom beams (e.g., Li, Na, K, Rb, Cs); charged ion beams (e.g., Ga+); or In place of an electron beam as radiation in lithographic process, we may also

# 3.6. FABRICATION OF QUANTUM DOT ARRAYS

single quantum well, the process starts with multiple quantum wells useful for many technological applications. In this case, instead of starting with a quantum dots possess unique quantum properties and cooperative interactions dots fabricated simultaneously for specific applications. These aggregates of 3-dimensions. Quantum dot arrays are the collection of a large number of quantum These are zero dimensional materials in which electrons are confined in material with diameters in the range 2 to 10 nm and made of about 10 to 50 atoms. Quantum dots are very small particles or nanocrystals of a semiconducting

Fig. 3.6. First of all a radiation sensitive resist is placed upon it, then a template or Let us consider a multiple (here four) quantum well structure as shown in mask film is used with six circles cut out of it. Following all the steps explained in Fig. 3.5, we can produce a 24 quantum dot array, in which there are six columns, each containing 4 stacked quantum dots as shown in Fig. 3.7.

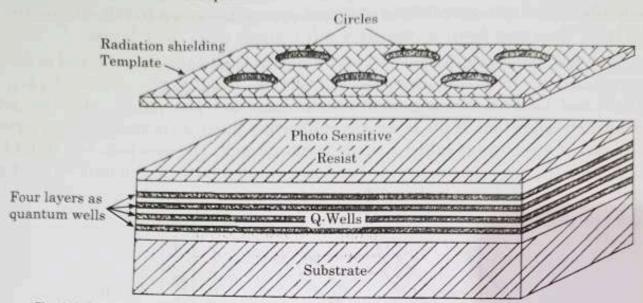


Fig. 3.6. Multiple-quantum-well arrangement mounted on a substrate and covered by a resist

The advantage of fabricating quantum dot arrays is that the arrays produce a greatly enhanced photo-luminescent (PL) output of light. Experiments have shown that a photo-luminescent spectrum from a quantum dot array is more than 100 times stronger than the spectrum obtained from the initial multiple quantum wells.

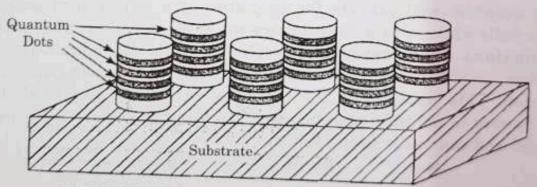


Fig. 3.7. 24-fold (or 6 × 4) quantum-dot array formed by lithography

# 3.7. QUANTUM WELL AND SUPERLATTICE I alea of Quantum well structure

The term 'well' refers to a semiconductor region that is grown to possess a lower energy, so that it acts as a trap for electrons and holes. These wells are called quantum wells because such semiconductor regions are only a few atomic layers thick. Quantum wells are real-world implementation of the "particle in one-dimensional box" problem. They are experimentally realized by epitaxial growth of a sequence of ultrathin layers consisting of semiconducting materials of varying composition (i.e., varying bandgap).

Quantum wells are formed in semiconductors by having a material like gallium arsenide (narrower band gap) sandwiched between two layers of a material with a wider band gap, like aluminium arsenide. These structures can be grown by molecular beam epitaxy (MBE) or chemical vapour deposition (CVD) with control of the layer thickness down to monolayers (i.e. single atom thick layers).

Two dissimilar semiconductors with different band gaps can be joined to form a heterojunction. If a thin layer of a narrower band gap material 'A' say, is sandwiched between two layers of a wider band gap material 'B', then we get a double heterojunction. If the layer A is sufficiently thin (i.e., in the quantum regime) then such a structure is called a single quantum well. The quantum well formed by the heterojunction between a wide band gap semiconductor and a narrow band gap semiconductor is shown in Fig. 3.8.

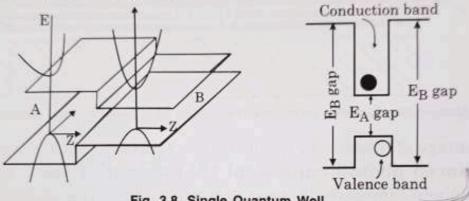
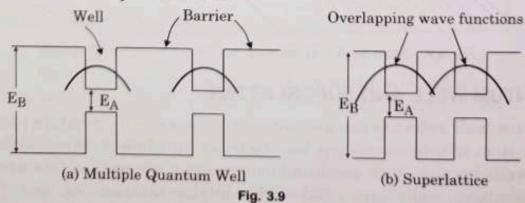


Fig. 3.8. Single Quantum Well

In the same manner we can form multiple quantum wells or superlattices. A multiple quantum well exhibits the properties of a collection of isolated single quantum wells whereas in a superlattice the barriers are very thin such that the wave functions of adjacent wells overlap strongly. In multiple quantum wells the barriers are wide enough such that wavefunctions in adjacent quantum wells do not overlap. This means that the tunneling probability from well to well is essentially zero in multiple quantum wells. However in superlattices electrons are delocalized and can easily tunnel out.



A superlattice can represent a lower dimensional structure such as an array of quantum dots or quantum wires. The periodic arrangement of quantum wells superimposes a different periodicity on top of the physical lattice, hence called a

superlattice. This gives rise to the formation of minibands within the superlattice. It should be noted that the same structure can be a multiple quantum well at low temperature and superlattice at room temperature.

### 3.7.1. Application of Schroedinger Equation to Infinite Potential Well

Let us now discuss the problem of quantum confinement along one direction. It is same as the problem of particle in one dimensional box. In a quantum well (2D structure), particles are confined to a thin sheet of thickness 'a' along the x direction by infinite potential barriers, which create a quantum well as shown in fig. 3.10.

In real systems, this confinement is due to electrostatic potentials (generated by external electrodes, doping, strain, impurities etc.); the presence of interfaces between different materials; the presence of surfaces; or a combination of these agents.

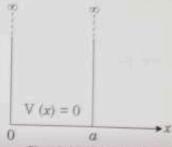


Fig. 3.10. Particle in infinitely deep potential

The potential function is

$$V(x) = \begin{cases} 0, & \text{for } 0 < x < a \\ \infty, & \text{for } x \le 0 \text{ or } x \ge a \end{cases}$$
 ... (1)

The Schroedinger equation in the potential well region where V(x) = 0, is

$$-\frac{\hbar^2}{2m}\frac{d^2\psi(x)}{dx^2} = E\psi(x)$$

$$\frac{d^2\psi}{dx^2} + \frac{2mE}{\hbar^2}\psi = 0$$

$$\frac{d^2\psi}{dx^2} + k^2\psi = 0 \qquad ... (2), \qquad k^2 = \frac{2mE}{\hbar^2}.$$

The boundary conditions are

or

or

$$\psi(0) = \psi(a) = 0$$
 ... (3)

The solution of equation (2) can be written as

$$\psi(x) = A\sin kx + B\cos kx \qquad ... (4)$$

Applying  $\psi(0) = 0$ , we get B = 0. So

$$\psi(x) = A \sin kx$$

Now  $\psi(a) = 0$  gives,  $A \sin ka = 0$ 

or 
$$\sin ka = 0 = \sin n\pi \qquad \qquad \because \quad A \neq 0$$
 or 
$$ka = n\pi, \quad n = 1, 2, 3, \dots$$

or 
$$k = \frac{n\pi}{a}$$

Thus, the solution of eqn. (2) is
$$\psi(x) = A \sin \frac{n\pi}{\alpha} x \qquad ... (5)$$

Applying the normalization condition of wave function

$$\int_{0}^{a} \psi * \psi dx = 1,$$

$$A = \sqrt{\frac{2}{a}}$$

$$\psi(x) = \sqrt{\frac{2}{a}} \sin \frac{n\pi}{a} x \qquad (6)$$

we get

represents normalized eigen functions of the particle inside the well.

Also, 
$$k^{2} = \frac{2mE}{\hbar^{2}},$$
 or 
$$\frac{n^{2}\pi^{2}}{a^{2}} = \frac{2mE}{\hbar^{2}}$$
 or 
$$E_{n} = E = \frac{n^{2}\pi^{2}\hbar^{2}}{2ma^{2}} = \frac{n^{2}h^{2}}{8ma^{2}} \qquad ... (7)$$

are the discrete energy states of the particle within the quantum well region. However, outside the well region particle energies are continuous. Here n is called the principal quantum number.

$$\begin{split} E_{(n+1)} - E_n &= \frac{\{(n+1)^2 - n^2\}\pi^2 \, \hbar^2}{2ma^2} = \frac{(2n+1)\pi^2 \, \hbar^2}{2ma^2} \\ (E_{(n+1)} - E_n) &\propto \frac{1}{a^2} \quad \text{and} \quad \propto (2n+1) \end{split}$$

or

As the dimension (=a) of the energy well increases, the spacing between discrete energy levels decreases. In the infinite crystal (i.e., bulk), a continuum occurs.

Above analysis shows that confinement of particle motion leads to discreteness or quantization of particle energies. The spacings between energy levels increases as principal quantum number n increases.

### Zero Point Energy

The lowest energy (for n = 1) in the above case is

$$E_0 = \frac{\pi^2 \hbar^2}{2ma^2} \neq 0$$

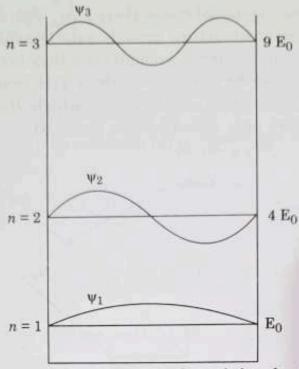


Fig. 3.11. First three eigen energies and eigen functions

This energy  $E_0$  is called the zero-point energy or confinement energy. Its origin lies in the Heisenberg's uncertainty principle. Since the particle is constrained within a finite region, the variability in its position has an upper bound *i.e.* uncertainty in its position is finite whose maximum value can be 'a'. Therefore uncertainty in particle's momentum cannot be zero, the particle must contain some energy in this lowest state. The zero point energy increases with decrease in the width of the well.

### 3.8. QUANTUM WIRES

It is a one-dimensional nanostructure in which there is confinement along two dimensions and only one dimension is free for motion of charge carriers. A quantum wire or nanowire can be obtained from a quantum well by the process of lithography.

A standard quantum well layer can be fabricated by the process of photolithography or electron beam lithography and chemically etched to leave a free standing strip of quantum well material; the latter may or may not be filled in with

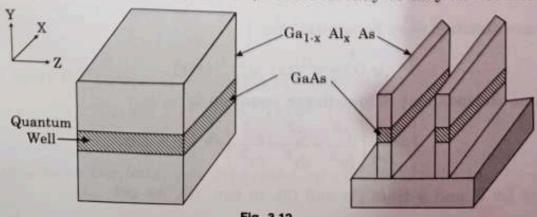
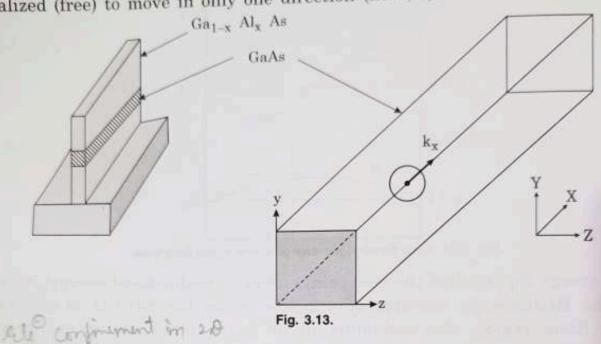


Fig. 3.12.

an overgrowth of the barrier material (here,  $Ga_{1-x}$   $Al_x$  As). Any charge carriers are still confined along the heterostructure growth axis (z-axis), as they were in the quantum well, but if the strip is narrow enough then they are also confined along an additional direction which may be either x- or the y-axis, depending on lithography, additional direction which may be either x- or the y-axis, depending on lithography. In the Fig. 3.13, a quantum wire is shown in which the electron (or hole) is delocalized (free) to move in only one direction (here, x).



### 3.8.1. Application of Schroedinger Equation to the Problem of Particle in 2D Box

The problem of a quantum wire is analogous to the particle in two dimensional box problem from the confinement point of view. Let us consider a two-dimensional

box as shown in Fig. 3.14. Let confinement is along y- and z-directions and the motion of the charge carrier is free along x-direction.

The potential V(r) is written as the sum of a two dimensional confinement potential (in the yz plane) plus a potential along the wire (i.e., along x-axis) as

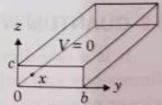


Fig. 3.14. Particle in 2D Box

$$V(r) = V^{(1)}(x) + V^{(2,3)}(y,z)$$
 ... (1)

The wave function may be written as

$$\psi(r) = \psi^{(1)}(x) \ \psi^{(2,3)}(y,z)$$
 ... (2)

The time independent Schroedinger equation is

$$\left\{ -\frac{\hbar^2}{2m} \left( \frac{\partial^2}{\partial x^2} + \frac{\partial^2}{\partial y^2} + \frac{\partial^2}{\partial z^2} \right) + V \right\} \psi = E \psi \qquad ... (3)$$

Putting for V and  $\psi$  from (1) and (2), in eqn. (3), we get

$$\left\{ -\frac{\hbar^2}{2m} \left( \frac{\partial^2}{\partial x^2} + \frac{\partial^2}{\partial y^2} + \frac{\partial^2}{\partial z^2} \right) + V^{(1)}(x) + V^{(2,3)}(y,z) \right\} \psi^{(1)}(x) \psi^{(2,3)}(y,z) 
= E \psi^{(1)}(x) \psi^{(2,3)}(y,z) \qquad \dots (4)$$

Writing  $E = E^{(1)} + E^{(2,3)}$  and noting the fact that potential is zero everywhere inside the box (i.e.,  $V^{(1)}(x) = 0$ ), equation (4) is equivalent to two equations which are as follows:

$$-\frac{\hbar^2}{2m}\frac{d^2\psi^{(1)}(x)}{dx^2} = E^{(1)}\psi^{(1)}(x) \qquad ... (5a)$$

and 
$$-\frac{\hbar^2}{2m} \left( \frac{\partial^2}{\partial y^2} + \frac{\partial^2}{\partial z^2} \right) \psi^{(2,3)}(y,z) + V^{(2,3)}(y,z) \psi^{(2,3)}(y,z) = E^{(2,3)}\psi^{(2,3)}(y,z) \dots$$
 (5b)

Equation (5a) may be written in the form  $\frac{\partial^2 \psi'(N)}{\partial \chi^2} + \frac{2mE'}{4^2} \psi'(N) = 0$ 

$$\frac{d^2 \psi^{(1)}(x)}{dx^2} + k_x^2 \psi^{(1)}(x) = 0, \quad \dots (6), \qquad k_x^2 = \frac{2mE^{(1)}}{\hbar^2}$$

It has plane wave solution given by

$$\psi^{(1)}(x) \approx \exp(i k_x x)$$

where  $k_x$  is the particle momentum along x-direction in which it is free to move with energy

$$E^{(1)} = \frac{\hbar^2 k_x^2}{2m} \qquad ... (7)$$

Now to solve equation (5b), the potential  $V^{(2,3)}(y,z)$  has the form

$$V^{(2,3)}(y,z) = \begin{cases} 0 & \text{when } 0 < y < b \text{ and } 0 < z < c \\ \infty & \text{otherwise} \end{cases}$$
 ... (8)

Outside the box,  $\psi^{(2,3)}(y,z) = 0$  because particle cannot be outside it. Thus, within the box, equation (5b) in the light of eqn. (8), reduces to

$$-\frac{\hbar^2}{2m} \left( \frac{\partial^2}{\partial y^2} + \frac{\partial^2}{\partial z^2} \right) \psi^{(2,3)}(y,z) = E^{(2,3)} \psi^{(2,3)}(y,z) \qquad ... (9)$$

To apply the method of separation of variables, let

$$\Psi^{(2,3)}(y,z) = \Psi^{(2)}(y) \Psi^{(3)}(z)$$

$$E^{(2,3)} = E^{(2)} + E^{(3)}$$

Using these two facts, eqn. (9) breaks into two equations as

$$-\frac{\hbar^{2}}{2m}\frac{d^{2}\psi^{(2)}(y)}{dy^{2}} = E^{(2)}\psi^{(2)}(y) / \frac{\partial^{1}\psi^{1}(y) + 2mE^{2}\psi^{1}(y) = 0}{\partial^{1}\psi^{1}(y)} = \dots (10a)$$

$$-\frac{\hbar^{2}}{2m}\frac{d^{2}\psi^{(3)}(z)}{dz^{2}} = E^{(3)}\psi^{(3)}(z) / \frac{\partial^{2}\psi^{3}(y)}{\partial y^{2}} + \frac{2mE^{3}\psi^{2}(y) = 0}{\partial y^{2}} \dots (10b)$$

and

These equations may be written as

equations may be written 
$$\frac{d^2 \psi^2(y)}{dy^2} + k_y^2 \psi^2(y) = 0 \qquad ...(11a); \qquad k_y^2 = \frac{2mE^{(2)}}{\hbar^2}$$

and

$$\frac{d^2 \psi^3(z)}{dz^2} + k_y^2 \psi^3(z) = 0 \qquad \dots (11b); \qquad k_z^2 = \frac{2mE^{(3)}}{\hbar^2}$$

Both of these equations are similar to the Schrodinger equation in the infinitely deep potential well and have the same boundary conditions too. The standard boundary condition of the wavefunction being continuous at the walls of the box implies that the product of  $\psi^{(2)}(y)$  and  $\psi^{(3)}(z)$  must vanish at the walls. These boundary conditions when applied to (11a) and (11b) give normalized eigen functions

$$\psi_{n_y}^{(2)}(y) = \sqrt{\frac{2}{b}} \sin\left(\frac{n_y \pi y}{b}\right); \ n_y = 1,2,3...$$

and

$$\psi_{n_z}^{(3)}(z) = \sqrt{\frac{2}{c}} \sin\left(\frac{n_z \pi z}{c}\right); \ n_z = 1,2,3...$$

Therefore,

$$\psi_{(n_y, n_z)}^{(2, 3)} = \sqrt{\frac{4}{bc}} \sin\left(\frac{n_y \pi y}{b}\right) \sin\left(\frac{n_z \pi z}{c}\right) \qquad \dots (12)$$

As is clear from (12), the quantum states in a quantum wire are described by two principal quantum numbers  $n_y$  and  $n_z$ . The energy levels of a quantum wire are given by

and

$$E_{n_{y}} = \frac{\pi^{2} \hbar^{2} n_{y}^{2}}{2m b^{2}}, \quad n_{y} = 1, 2, 3, ...$$

$$E_{n_{z}} = \frac{\pi^{2} \hbar^{2} n_{z}^{2}}{2m c^{2}}, \quad n_{z} = 1, 2, 3, ...$$
... (13)

The energy associated with particle motion in free direction (i.e., x-) is

$$E(k_x) = \frac{\hbar^2 \ k_x^2}{2m} \qquad ...(14)$$

Thus, total energy of the particle in a quantum wire is given by

$$E_{(n_y, n_z)}(k_x) = \frac{\hbar^2 k_x^2}{2m} + \frac{\pi^2 \hbar^2 n_y^2}{2mb^2} + \frac{\pi^2 \hbar^2 n_z^2}{2mc^2} \qquad ...(15)$$

Thus, the energy of the particle along the confinement directions (y and z) is discrete whereas it can have any value along unconfined (or free) direction (i.e., along x-axis). Total energy of the particle in a quantum wire is not discrete. Further, the eigen energy in a quantum wire increases for decreasing size and a lower effective mass results in a larger eigen energy for a given size of the box.

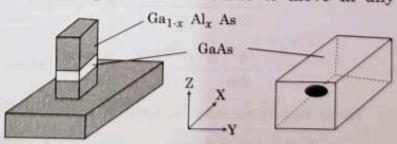
The applications of nanowires are due to the fact that besides exhibiting quantum confinement effects, nanowire materials are at the same time in the shape of wires. So making electrical connections to the outside world and assembling actual devices may be a lot easier than with other nanostructures, such as quantum dots or quantum wells.

Crossed nanowire junctions have been made, using p-type and n-type nanowires. These may be used as diodes, or memory elements or as electro luminescent devices (LEDs or Solar Cells). Nanowires have also been used as sensors for monitoring changes in the conductance experienced when different compounds or gases are adsorbed to the surface of the nanowire. Thus, in future, nanowires may serve as efficient sensors for minute amounts of toxic gases, chemical weapons and explosives.

### 3.9. QUANTUM DOTS

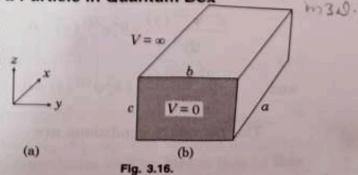
It is a zero dimensional nano-structure in which there is confinement of the particle along all the three directions. The particle is not free to move in any

direction. Quantum dots have their radii in the typical range of 2 to 10 nm. Quantum dots can be formed by lithography and etching if a quantum well sample is etched to leave pillars rather than wires as shown in Fig. 3.15.



3.9.1. Application of Schroedinger Equation to a Particle in Quantum Box

Let us discuss the problem of quantum dot from confinement point of view. We consider a cuboid quantum dot or quantum box as shown in Fig. 3.16(b). Spherical quantum dots require numerical solution of Schroedinger equation. The quantum box is a generalization of a quantum wire of rectangular cross-section in which there is additional confinement along



cle confinement

the x-direction such that 0 < x < c. Thus, the particle has no degrees of freedom in its momentum and it is now localized in all the three directions. Hence, it has discrete energy states associated with all the three directions of motion.

Let the potential be zero inside the quantum box but infinite everywhere else

i.e.,

$$V(x,y,z) = \begin{cases} 0 & \text{for } 0 < x < a, 0 < y < b \text{ and } 0 < z < c \\ \infty & \text{otherwise} \end{cases}$$
 ... (1)

Three dimensional time independent Schroedinger equation within the box (V=0), is

$$-\frac{\hbar^2}{2m}\left(\frac{\partial^2}{\partial x^2} + \frac{\partial^2}{\partial y^2} + \frac{\partial^2}{\partial z^2}\right)\psi(x,y,z) = E\psi(x,y,z) \qquad \dots (2)$$

The wave function may be written as a product

$$\psi(x,y,z) = \psi^{(1)}(x)\psi^{(2)}(y)\psi^{(3)}(z) \qquad ... (3)$$

and the energy can be written as a sum

$$E = E^{(1)} + E^{(2)} + E^{(3)} \qquad ... (4)$$

where  $E^{(1)}$ ,  $E^{(2)}$ ,  $E^{(3)}$  are particle energies along x, y and z directions respectively.

Using (3) and (4) in equation (2), which then separates into three equations as

$$-\frac{\hbar^2}{2m} \frac{d^2 \psi^{(1)}(x)}{dx^2} = E^{(1)} \psi^{(1)}(x) \qquad ... (5a)$$

$$-\frac{\hbar^2}{2m}\frac{d^2\psi^{(2)}(y)}{dy^2} = E^{(2)}\psi^{(2)}(y) \qquad ... (5b)$$

or

$$-\frac{\hbar^2}{2m} \frac{d^2 \psi^{(3)}(z)}{dz^2} = E^{(3)} \psi^{(3)}(z) \qquad ... (5c)$$

These equations may be written in simple form as

$$\frac{d^2 \psi^{(1)}(x)}{dx^2} + k_x^2 \psi^{(1)}(x) = 0, \qquad k_x^2 = \frac{2mE^{(1)}}{\hbar^2} \qquad \dots (6a)$$

$$\frac{d^2 \psi^{(2)}(y)}{dy^2} + k_y^2 \psi^{(2)}(y) = 0, \qquad k_y^2 = \frac{2mE^{(2)}}{\hbar^2} \qquad \dots (6b)$$

and 
$$\frac{d^2 \psi^{(3)}(z)}{dz^2} + k_z^2 \psi^{(3)}(z) = 0, \qquad k_z^2 = \frac{2mE^{(3)}}{\hbar^2} \qquad \dots (6c)$$

The boundary conditions are

$$\psi^{(1)}(x) = 0$$
 at  $x = 0$  and  $x = a$ 

$$\psi^{(2)}(y) = 0$$
 at  $y = 0$  and  $y = b$ 

$$\psi^{(3)}(z) = 0$$
 at  $z = 0$  and  $z = c$ 

The normalized plane wave solutions of above equations on using boundary conditions of continuity of wave functions at the walls of the box, are

$$\Psi_{n_x}^{(1)}(x) = \sqrt{\frac{2}{a}} \sin\left(\frac{n_x \pi x}{a}\right) \qquad \dots (7a)$$

$$\psi_{n_y}^{(2)}(y) = \sqrt{\frac{2}{b}} \sin\left(\frac{n_y \pi y}{b}\right)$$
 ... (7b)

 $\Psi_{n_z}^{(3)}(z) = \sqrt{\frac{2}{c}} \sin\left(\frac{n_z \pi z}{c}\right)$ ... (7c)

The eigen energies are given by

$$\begin{split} E_{n_x}^{(1)} &= \frac{\hbar^2 k_x^2}{2m} = \frac{\pi^2 \hbar^2 n_x^2}{2ma^2} & \dots (8a), \quad k_x = \frac{n_x \pi}{a} \\ E_{n_y}^{(2)} &= \frac{\hbar^2 k_y^2}{2m} = \frac{\pi^2 \hbar^2 n_y^2}{2mb^2} & \dots (8b), \quad k_y = \frac{n_y \pi}{b} \\ E_{n_z}^{(3)} &= \frac{\hbar^2 k_z^2}{2m} = \frac{\pi^2 \hbar^2 n_z^2}{2mc^2} & \dots (8c) \quad k_z = \frac{n_z \pi}{c} \end{split}$$

Thus, the complete eigen functions of a quantum dot or a particle in quantum box are

$$\Psi_{n_x, n_y, n_z}(x, y, z) = \sqrt{\frac{8}{abc}} \sin\left(\frac{n_x \pi x}{a}\right) \sin\left(\frac{n_y \pi y}{b}\right) \sin\left(\frac{n_z \pi z}{c}\right) \qquad \dots (9)$$

which involves three principal quantum numbers whose values are

$$n_x = 1, 2, 3, ...;$$
  $n_y = 1, 2, 3, ...;$   $n_z = 1, 2, 3, ...$ 

Also the eigen energy corresponding to an eigen function is given by

$$E_{n_x, n_y, n_z} = E_{n_x}^{(1)} + E_{n_y}^{(2)} + E_{n_z}^{(3)}$$

$$E_{n_x, n_y, n_z} = \frac{\pi^2 \hbar^2}{2m} \left( \frac{n_x^2}{a^2} + \frac{n_y^2}{b^2} + \frac{n_z^2}{c^2} \right) \qquad \dots (10)$$

As is clear from equation (10), the total energy of a quantum dot,  $E_{n_x,n_y,n_z}$ , is discrete depending upon three quantum numbers  $n_x$ ,  $n_y$ ,  $n_z$ . The striking difference between between the case of a quantum dot and that of a quantum well or wire is that in this

and

or

case total energy is quantized whereas in the well or wire case only the energy associated with the directions of confinement is quantized. This quantization feature associated with the directions of quantum boxes are sometimes is typical of atoms, therefore quantum dots or quantum boxes are sometimes referred to as artificial atoms.

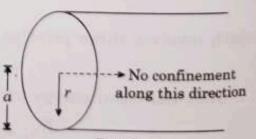
A remarkable feature of a quantum box is that when two or more of the dimensions are the same (e.g., a = b), more than one eigenfunction corresponds to the same total energy. Such eigen values are called degenerate eigen values and the number of eigen functions corresponding to it is called degeneracy of that energy level. Degeneracy results from the symmetry of the structure.

Quantum dots have following applications:

- 1. Quantum dots, particularly CdSe, have narrow emission spectra and since different sized dots emit different colours, therefore these dots may be used for biological labeling. Dots are much more resistant to fading. However, labeling of proteins or cells or other biological specimen, is done with the help of organic dyes not with quantum dots.
  - 2. Colloidal CdSe quantum dots may be used in efficient multicolour lasers.
- 3. Since quantum dots have tunable, size dependent absorption and emission spectra, therefore they may be used in fabricating efficient solar cells which can operate even under cloudy conditions and on rainy days.
- 4. Since different sized quantum dots emit different colours, therefore quantum dots may be used in making light emitting devices (LEDs).
- 5. Quantum dots may be used as conducting islands in single electron transistors (SETs) due to confinement effects. Quantum dots may be used to store charge and hence can be used in a memory device.

### 3.10. PARTICLE IN AN INFINITE CIRCULAR BOX: TWO DIMENSIONS OF CONFINEMENT

This case of confinement is concerned with a quantum wire of circular cross-section. Let the particle is confined to a circular cross-section of the T wire with radius 'a'. The particle is free to move along a the length of the wire. The potential in this case is represented by



$$V(r) = \begin{cases} 0 & \text{if } r < a \\ \infty & \text{if } r \ge a \end{cases}$$
 Fig. 3.17.

The time independent Schroedinger equation relevant to this case is

$$-\frac{\hbar^2}{2m}\nabla^2\psi + V\psi = E\psi$$

### 4.1. INTRODUCTION

Density of states (DOS) is defined as the number of different states at a given energy level that electrons are allowed to occupy. The DOS is a measure of how close together the energy levels are to each other. In three dimensional structures it is equal to the number of electron states per unit volume per unit energy interval. It is represented by g(E). If dN be the number of available electron states per unit volume at energy E in the energy interval E to E+dE, then density of states is defined as:

$$g(E) = \frac{dN(E)}{dE} \qquad \dots (1)$$

The calculation of some electronic processes like absorption, emission, and the general distribution of electrons in a material requires the knowledge of the number of available states per unit volume per unit energy range *i.e.*, the density of states, Bulk properties such as specific heat, paramagnetic suceptibility, and other transport phenomena of conductive solids depend on density of states function. The behaviour of density of states function with respect to the energy depends upon the dimensionality of the system (material). The density of states function provides useful information about the electronic structure of 3D (bulk), 2D (quantum well), 1D (quantum wire) and 0D (quantum dot) materials. The density of states can be used to determine the spacing between energy bands in semiconductors. In this chapter we will derive expressions for density of states for materials of different dimensions.

### 4.2. DENSITY OF STATES IN THREE DIMENSIONS (BULK)

Let us first calculate the density of states for a bulk (3D) material in which there is no confinement at all. Thus, there are three degrees of freedom and the electrons are free to move along all the three (x, y, z) directions. The energy E is related to the propagation constant k (magnitude of wave vector) as

$$E = \frac{\hbar^2 k^2}{2m} \qquad \dots (1)$$

Consider the volume in reciprocal space (i.e., k space)

$$V_{k} = \frac{4}{3}\pi k^{3}$$

$$k^{2} = k_{x}^{2} + k_{y}^{2} + k_{z}^{2}$$

$$k_{x} = \frac{2\pi}{L_{x}}, \quad k_{y} = \frac{2\pi}{L_{y}}, \quad k_{z} = \frac{2\pi}{L_{z}}.$$

and

where

Here  $L_x$ ,  $L_y$ ,  $L_z$  are the length of the material along x, y, z directions. The factor of  $2\pi$  occurs due to the application of periodic boundary conditions on the material. A set of  $(k_x, k_y, k_z)$  values represents a mode. Thus

Volume occupied by each mode =  $k_x \cdot k_y \cdot k_z$ =  $\frac{(2\pi)^3}{L_x L_y L_z}$ 

Therefore the number of modes in the spherical volume  $V_k$  are given by

$$= \frac{\text{Volume of sphere}}{\text{Volume of each mode}} = \frac{V_k}{k_x k_y k_z} = \frac{\frac{4}{3} \pi k^3}{(2\pi)^3 / L_x L_y L_z}$$

For electrons, there are two states (spin up and spin down) with same energy, then the number of electron states (or modes) in the volume  $\boldsymbol{V}_k$  are

$$= 2 \times \frac{\frac{4}{3}\pi k^{3}}{(2\pi)^{3}/L_{x} L_{y} L_{z}}$$

$$= \frac{k^{3}}{3\pi^{2}} L_{x} L_{y} L_{z} \qquad ... (2)$$

The number of electron states per unit volume of the material

$$N = \frac{\text{Total number of states}}{\text{Volume of the specimen}} = \frac{\frac{k^3}{3\pi^2} L_x L_y L_z}{L_x L_y L_z}$$

$$N = \frac{k^3}{3\pi^2} \dots (3)$$

.. Density of states

$$g(E) = \frac{dN}{dE} = \frac{d\left(\frac{k^3}{3\pi^2}\right)}{dE}$$

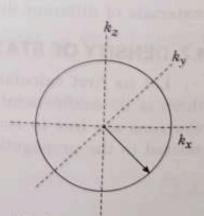


Fig. 4.1. Spherical k-space

$$= \frac{1}{3\pi^2} \frac{3k^2 dk}{dE} = \frac{k^2}{\pi^2} \left( \frac{dk}{dE} \right)$$
 ... (4)

From equation (1),

$$k^2 = \frac{2mE}{\hbar^2} \text{ or } k = \sqrt{\frac{2mE}{\hbar^2}}$$
 
$$dk = \sqrt{\frac{2m}{\hbar^2}} \frac{1}{2} E^{-1/2} dE$$

Putting these values in equation (4), we get

$$g(E) = \frac{1}{\pi^2} \times \frac{2mE}{\hbar^2} \times \sqrt{\frac{2m}{\hbar^2}} \frac{1}{2} E^{-1/2}$$

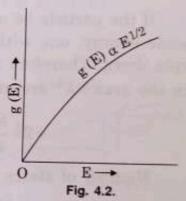
$$g(E) = \frac{1}{2\pi^2} \left(\frac{2m}{\hbar^2}\right)^{3/2} E^{1/2} \qquad ... (5)$$

or

This is the "density of states" in three dimensions. It is clear that

$$g(E) \propto E^{1/2}$$

Thus density of states of a bulk three dimensional material is a parabolic function of its energy. Fig. 4.2. shows a plot of g(E) versus E for a bulk three dimensional material. Clearly, density of states in three dimensional system increases with increase in energy of the system.



# 4.3. DENSITY OF STATES IN TWO DIMENSIONS (QUANTUM WELL)

In a two-dimensional material such as a quantum well, electron motion is confined along one direction (say, z) and they are free to move along rest of the two directions (x, y). Thus electron energy is quantized in one dimension. Total energy of this material is the sum of the energy along the quantized direction and the energy along the other two (i.e., free) directions. It can be expressed as

$$E = \frac{\hbar^2 k_z^2}{2m} + \frac{\hbar^2 k^2}{2m} = E_n + E_{x,y}$$
 ... (1)

where  $k^2 = k_x^2 + k_y^2$  and  $k_z = \frac{n\pi}{L_z}$ . Here n = 1, 2, 3, ... is an integer.

Let us now consider the circular area of k space

$$A_k = \pi k^2$$

Hence along x and y directions the particle is free to move, therefore due to periodic boundary conditions

$$k_{x} = \frac{2\pi}{L_{x}}$$

$$k_{y} = \frac{2\pi}{L_{y}}$$

Area of each mode =  $k_x k_y = \frac{(2\pi)^2}{L_y L_y}$ 

... (2)

Total number of modes in the area  $A_k$  is given by

$$= \frac{\text{Total area}}{\text{Area of each mode}} = \frac{\pi k^2}{(2\pi)^2 / L_x L_y}$$

$$=\frac{k^2}{4\pi}L_xL_y \qquad ... (3)$$

If the particle be an electron, then there can be two electrons corresponding to same energy, one with spin up and the other with spin down. Therefore total number of energy states in the area  $\pi k^2$  are given by

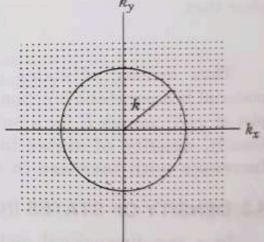
$$= 2 \times \frac{k^2}{4\pi} L_x L_y = \frac{k^2}{2\pi} L_x L_y \qquad ... (4)$$

Number of states per unit area

$$N = \frac{\text{Total number of states}}{\text{Area}}$$

$$= \frac{\frac{k^2}{2\pi} L_x L_y}{L_x L_y}$$

$$=\frac{k^2}{2\pi}$$



Density of states

$$g(E) = \frac{dN}{dE} = \frac{d(k^2/2\pi)}{dE} = \frac{k}{\pi} \left(\frac{dk}{dE}\right)$$

..

$$E = \frac{\hbar^2 k^2}{2m}$$
 (along free directions)

$$k = \sqrt{\frac{2m}{\hbar^2}} E^{1/2}$$

$$dk = \sqrt{\frac{2m}{\hbar^2}} \, \frac{1}{2} \, E^{-1/2} \, dE$$

Substituting the values of k and dk in the above expression, we get

$$g(E) = \frac{1}{\pi} \left( \frac{2mE}{\hbar^2} \right)^{1/2} \times \left( \frac{2m}{\hbar^2} \right)^{1/2} \frac{1}{2} E^{-1/2}$$

$$g(E) = \frac{m}{\pi \hbar^2} \qquad ... (6)$$

or

This is the energy density of the subband for a given  $k_z$  (or  $E_n$ ). For each successive  $k_z$  there will be an additional  $m/\pi \hbar^2$  term and hence another subband. The density of states is therefore expressed as

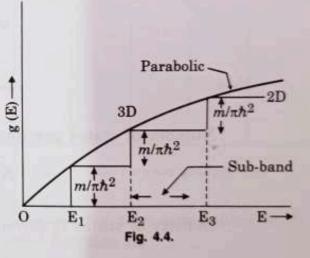
$$g(E) = \frac{m}{\pi \hbar^2} \sum_{n} \Theta(E - E_n) \qquad ... (7)$$

where  $\Theta$  is the Heaviside function or unit step function and is given by

$$\Theta(E - E_n) = \begin{cases} 0 & \text{for } E < E_n \\ 1 & \text{for } E > E_n \end{cases} \dots (8)$$

The plot of g(E) versus E for a two-dimensional material like quantum well is shown in fig. 4.4. The resulting density of states for a quantum well is a **staircase**.

Clearly in each subband, the density of states is a constant *i.e.*, independent of energy. The difference in the density of states of two consecutive sub-bands is  $m/\pi\hbar^2$ .



### 4.4. DENSITY OF STATES IN ONE DIMENSION (QUANTUM WIRE)

In a one dimensional material such as a quantum wire, particle motion is confined along two directions (say y, z) and free along one direction (say x). Thus there is only one degree of freedom. Particle energy is quantized for motion along y and z directions. Total energy of the system can be written as the sum of the energy along the quantized directions (y, z) and the energy along the free direction (x), i.e.,

$$E = \frac{\hbar^2 k_y^2}{2m} + \frac{\hbar^2 k_z^2}{2m} + \frac{\hbar^2 k^2}{2m} = E_l + E_n + E_x \qquad \dots (1)$$

where  $k = k_x = \frac{2\pi}{L_x}$ . For the confined directions, we have

$$k_y = \frac{l\pi}{L_y}$$

$$k_z = \frac{n\pi}{L_z}$$

where l, n = 1, 2, 3, ... are integers. We consider a length 2k in k-space. The number of

modes (states) along this length

$$=\frac{2k}{k_x}=\frac{2k}{2\pi/L_x}=\frac{k}{\pi}L_x$$

If the particle be an electron then there can be two electrons one with spin up and other with spin down, corresponding to each energy. Therefore the number of states along the length  $k_x$  is

$$=2\times\frac{k}{\pi}L_x=\frac{2k}{\pi}L_x$$

Number of states per unit length

$$N = \frac{2k}{L_x} L_x = \frac{2k}{\pi}$$

$$k = \sqrt{\frac{2mE}{\hbar^2}}$$
... (2)

Now

Number of states per unit length

$$N = \frac{2}{\pi} \sqrt{\frac{2mE}{\hbar^2}} \qquad ... (3)$$

Density of states is given by

$$g(E) = \frac{dN}{dE} = \frac{2}{\pi} \sqrt{\frac{2m}{\hbar^2}} \frac{d(\sqrt{E})}{dE} = \frac{2}{\pi} \sqrt{\frac{2m}{\hbar^2}} \times \frac{\frac{1}{2}E^{-1/2} dE}{dE}$$

$$g(E) = \frac{1}{\pi} \sqrt{\frac{2m}{\hbar^2}} E^{-1/2} = \frac{1}{\pi} \sqrt{\frac{2m}{\hbar^2 E}} \qquad ... (4)$$

or

This is the energy density for a given n, l value or  $(E_n, E_l$  combination). This clearly shows that the density of states of a one dimensional system (quantum wire) decreases with increase in energy for every (n, l) combination.

By taking into account all n, l combinations, the complete expression for density of states is expressed as

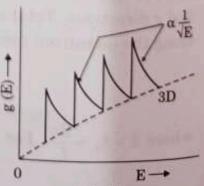


Fig. 4.5.

$$g(E) = \sqrt{\frac{2m}{\pi^2 \hbar^2}} \sum_{n,l} \frac{1}{\sqrt{E - E_{n,l}}} \Theta (E - E_{n,l}) \qquad ... (5)$$

where  $\Theta$   $(E-E_{n,l})$  is the Heaviside or unit step function. The plot of g(E) versus E for a quantum wire is shown in Fig. 4.5.

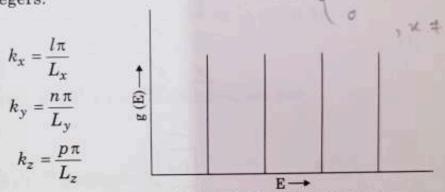
### 4.5. DENSITY OF STATES IN ZERO DIMENSIONAL SYSTEM (QUANTUM DOT)

In the extreme case of confinement along all the three directions, particle is not free to move at all. Its motion is confined along all the three directions x, y, z. The resultant material or nanostructure is called a quantum dot or nanoparticle. The energy of the particle is quantized along all the three directions x, y, z. Therefore total energy of the system is quantized and is given by

$$E = \frac{\hbar^2 k_x^2}{2m} + \frac{\hbar^2 k_y^2}{2m} + \frac{\hbar^2 k_z^2}{2m} = E_l + E_n + E_p \qquad \dots (1)$$

where l, n, p = 1, 2, 3,... are integers.

Also



In this case there is no k-space to be filled with electrons and all available states exist

Fig. 4.6. DOS for Ideal quantum dots

only at discrete energies. Hence the density of states for a zero dimensional (0D) system i.e., a quantum dot is expressed by a delta function as

$$g(E) = \delta(E - E_{n,l,p}) \qquad \dots (2)$$

Fig. 4.6. shows the plot of g(E) versus E for a zero dimensional material.

In real quantum dots, the size distribution leads to a broadening of the delta (line) function as shown in the Fig. 4.7.

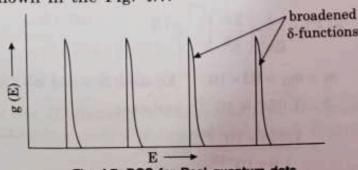


Fig. 4.7. DOS for Real quantum dots

# 4.6. COMPARISON OF DOS FOR 3D, 2D, 1D AND 0D NANOSTRUCTURES

The variation of density of states (DOS) with energy for bulk, quantum well,

quantum wire and quantum dot is shown below :

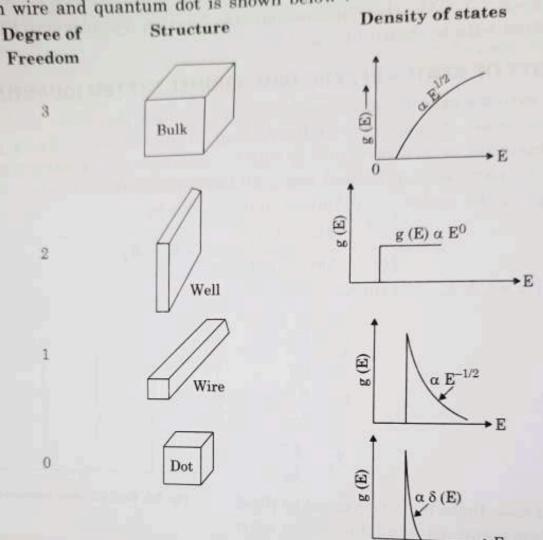


Fig. 4.8. Comparison of DOS

# Solved Examples

Ex. 1. Calculate the density of states of electrons of energy 0.1 eV in three dimensions. Express the result in terms of eV and cm 3.

Sol. The electronic density of states in three dimensions is given by

$$g(E) = \frac{1}{2\pi^2} \left(\frac{2m}{\hbar^2}\right)^{3/2} E^{1/2}$$
Given that,
$$m = m_0 = 9.1 \times 10^{-31} \text{ kg and } E = 0.1 \text{ eV}$$

$$h = 1.054 \times 10^{-34} \text{ joule-sec}$$

$$= \frac{1.054 \times 10^{-34}}{1.6 \times 10^{-19}} \text{ eV. sec}$$

$$= 0.65875 \times 10^{-15} \text{ eV.sec.}$$

affected by the surrounding environment. During biological synthesis, the nanoparticles form a coating that makes them thicker and larger sized. The environment also influences the physical structure and chemistry of the synthesized nanoparticles.

Besides the above discussed factors, there are certain other parameters (or factors) that greatly influence the nature of nanoparticles being synthesized.

### 5.3. TOP-DOWN APPROACHES

Top-down approaches of synthesizing nanomaterials use macroscopic initial structures, which can be externally controlled in the processing of nanostructures. Typical examples are etching through the mask, ball milling, cutting, grinding and application of severe plastic deformation, photolithography, e-beam lithography etc.

Top-down methods begin with a pattern generated on a larger scale, which is reduced to nanoscale after a sequence of operations is performed over them. The major drawback of these methods is that they require large installations and huge capital is required for building their set-up. Therefore these methods are quite expensive. Moreover the growth process is slow and hence these methods are not suitable for large scale production. However top-down methods are very suitable for laboratory experimentation.

Top-down approaches are based on grinding of material. Thus these processes are subtractive in nature. The parts of mechanical devices used to shape objects are stiff and hard, so these methods are not suitable for soft samples. The top-down approach anticipates nanodevices that must be built piece by piece in a number of approach like manufactured items are made. Scanning probe microscopy (SPM) stages, much like manufactured items are made.

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is an important technique used both for synthesis and characterization of nanomaterials by top-down approach. Atomic force microscope (AFM) tips can be used as a nanoscale "write head" to deposit a resist, which is then followed by an etching process to remove material in a top-down method. Very high quality thin films can be deposited with nanometer control perpendicular to the plane of a substratum and this method is called physical vapour deposition (PVD). In this method the material to be deposited is evaporated from the reservoir or sputtered from the target.

Chemical vapour deposition (CVD) is another technique for the synthesis of nanostructures using top-down approach. In this method, the precursor (which is a compound that participates in a chemical reaction that produces another compound) of the thin layer is a reactive gas or mixture of gases and the substratum is typically heated to accelerate chemical reaction to form a solid product deposited as a film. The decomposition can be enhanced with a plasma. In MOCVD, the growth of crystals is by chemical reactions instead of physical deposition (as in MBE).

Metal-Organic Chemical Vapour Deposition (MOCVD) also known as Vapour Phase Epitaxy (MOVPE) takes place not in a vacuum, but from the gas phase at moderate pressures (2 to 100 kPa). This is a suitable technique for growing compound semiconductors from the surface reaction of organic compounds and metal hydrides containing the required chemical elements.

Ion implantation is used to modify existing surfaces of materials. In this method, electrostatically charged high energy (10-100 Kev) ions are directed towards the surface, where they arrive with kinetic energies several orders of magnitude higher than the binding energy of the host material, and become implanted in a surface layer that may be tens of nanometers thick.

In the top-down approach nano-objects are obtained from larger entities without atomic level control. Many technologies that emerged out of conventional solid state silicon methods for fabricating microprocessors are now capable of creating features smaller than 100 nm, which lie in the domain of nano-technology. Giant magneto resistance (GMR) based hard drives which have been already commercialized use top-down approach. Top-down methods can also be used nano-electromechanical systems (NEMS). Top-down methods use lithography in which a bulk material is reduced in size to nanoscale pattern. In top-down approach cutting, milling and shaping of materials into the desired shape and order takes place.

Electron beam lithography and X-ray lithography have been developed as an alternative to photolithography technique used in top-down methods. However electron beam technique is very expensive and also very slow. In top-down methods the starting material is generally solid. In these methods the material suffers an increase in surface defects since the material is subjected to internal stress.

### 5.4. BOTTOM-UP APPROACHES

of nanomaterials include approaches of synthesis miniaturization of materials components to atomic level with further self assembly process leading to the formation of nanostructures. During self assembly the physical forces operating at nanoscale combine basic units into larger stable structures. Typical examples are quantum dot formation during epitaxial growth and formation of nanoparticles from colloidal dispersion, physical vapour deposition chemical vapour deposition etc.

In the bottom-up methods we start with atoms or molecules and build nano. structures by the direct manipulation of atoms or molecules. Bottom-up methods involve atom-by atom, molecule-by-molecule or cluster-by-cluster manipulation for synthesis of nanostructures. In these methods the starting material is either in liquid state or gaseous state. These techniques include chemical synthesis. self-assembly and positional assembly. Dual polarisation interferometry is one tool suitable for characterization of self assembled thin films.

Bottom-up approach is based on the principle of molecular recognition (i.e., self assembly). Self assembly means growing more and more things of one's kind from themselves. The idea of self assembly (shake and bake) is to gather precursors in random positions and orientations and supply energy (shaking) to allow them to sample configuration space. The hugeness of this space suggests that a convergent pathway is inherent in the process in order to allow it to be completed in a reasonable time. Once the precursors are in position, "baking" may be required to strengthen the bonds connecting them and fix the final object permanently.

Many biological systems exhibit remarkable capabilities of assembling themselves starting from a randomly arranged mixture of components. The examples are bacteriophage virus, and proteins and ribonucleic acids (RNA) which can be spontaneously transformed from a random coil of the linear polymer to a compact, ordered 3D structure. In this approach the starting precursors of the final structures have to be very carefully designed.

The highly specialized chemistry of living systems, the fragility of many of its products and its inherent variability at many levels have made self assembly unsuitable for mimicking directly and incorporating into our present industrial system.

Bottom-up approaches are capable of producing devices in parallel and much cheaper than top-down methods but becomes difficult as the size and complexity of the desired assembly increases. Most useful structures require complex and thermodynamically unlikely arrangements of atoms. Watson-Crick base pairing and enzyme substrate interactions are notable examples of self assembly based on molecular recognition in biology. Approaches from the field of "Classical Chemical" synthesis also aim at designing molecules with well defined shape. AFM tips can be used as a nanoscale "write head" to deposit a chemical upon a surface in a desired pattern in a process called dip pen nano-lithography.

In the bottom-up methods high precision actuators (devices that convert electrical energy to mechanical energy and vice-versa) move atoms from place to place. Micro tips such as AFM tips emboss or imprint materials. Electron or ion beams are directed onto the surface at which device is to be grown.

Nature uses self-assembly in ultra-fine ways. The natural world is self assembled. In nature, spontaneous organization of molecules into stable, structurally well defined aggregates of nanometer dimensions takes place. Molecules can be transported to surfaces through liquids to form self-assembled monolayers (i.e. single atom thick layers). Atomic layer deposition (ALD) is one of the bottom-up methods which is very useful in depositing thin atomic layers on a substrate. Bottom-up methods provide improved nanostructures with less or defect free, homogeneous and long and short range orders.

### 5.5. BALL MILLING

A ball mill is a device used to grind and blend materials for use in mineral dressing processes, paints, pyrotechnics, ceramics and selective laser sintering. It is a physical method of synthesis of nanoparticles and is an example of top down approach of producing nanomaterials.

The ball mill consists of a hollow cylindrical shell which rotates about its axis. The axis of the shell may be either horizontal or inclined at a small angle to the horizontal. It is partially filled with the balls which may be made of chrome steel, stainless steel, ceramic or rubber. These balls form the grinding media of the ball mill. The inner surface of the cylindrical shell is generally lined (i.e, coated) with an abrasion resistant material e.g., rubber or mangenese steel. Rubber is preferred for this purpose due to less wear in mills lined with rubber. The length and diameter of the ball mill are nearly equal.

Principle: A ball mill works on the principle of impact and attrition (i.e.

friction). The size reduction is carried out by impact as the balls drop from near the top of the shell. In a continuously operated ball mill, the material to be ground is fed from the left through a 60° cone and the resulting material (product) is discharged through a 30° cone to the right both not shown in the figure 5.2. With the rotation of the shell, the balls are lifted up on the rising side of the shell and then they drop down on to

